

High-Density 3D Power Packaging with Heterogeneous Passive-Active Integration

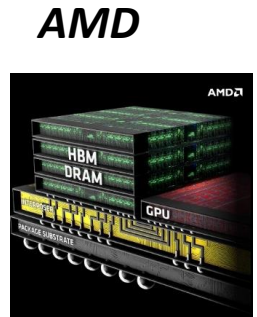
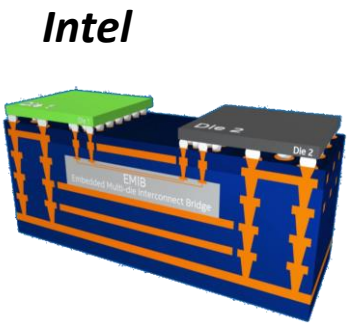
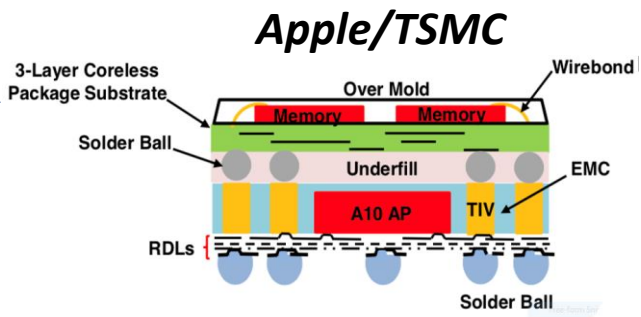
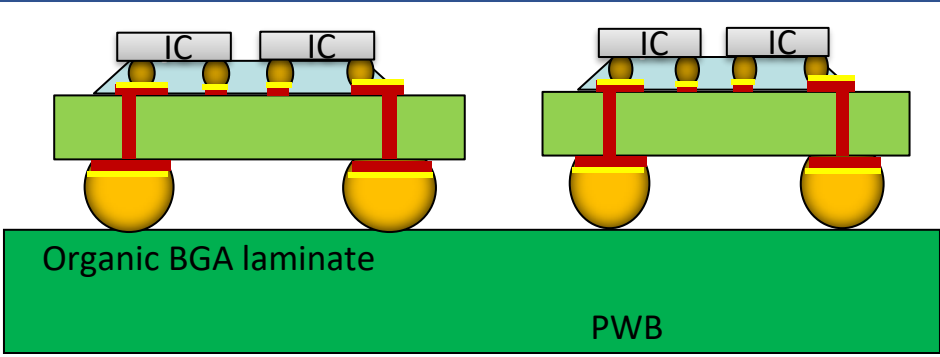
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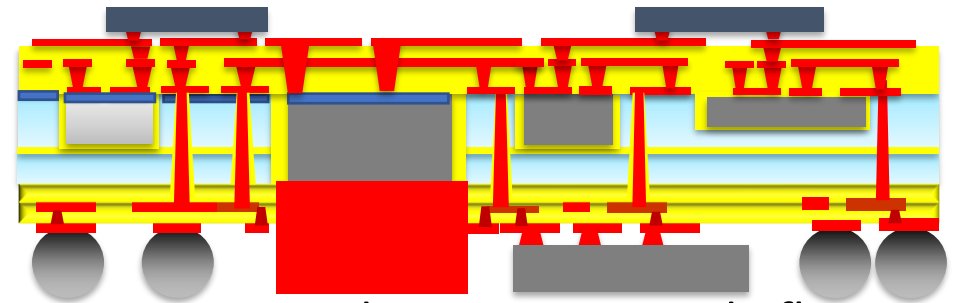
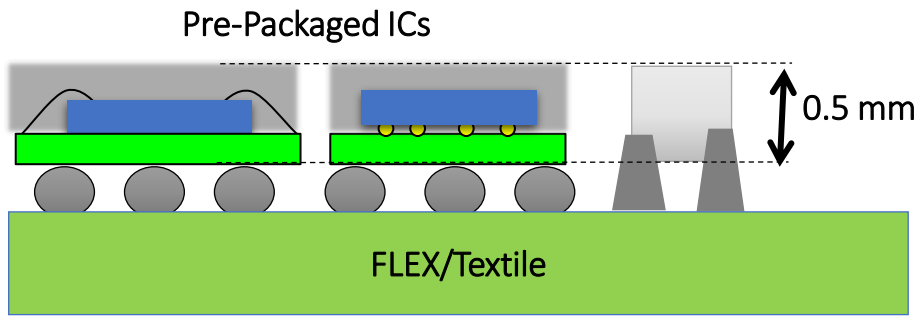
Heterogeneous Integration with Nanopackaging

- Power delivery in computing systems
 - Integrated voltage regulator
 - Capacitors and Inductors
- Medium-power packaging
 - Embedded-die packaging with die-attach materials
 - High-temperature organic packaging
- High-Power packaging:
 - Doubleside cooling
 - High-voltage passives

3D Heterogeneous Package Integration



2D packaging to 3D high-density packaging



Pre-packaged components on flex to embedded components and connectors inside flex

Pre-packaged and molded devices

Large power components and RF interfaces

2D Surface assembly

Traditional PCB processes

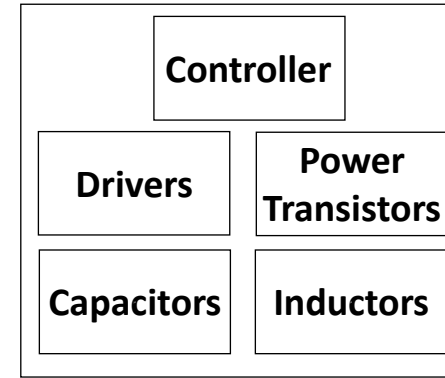


2.5D or 3D integration: logic-memory, transceiver-Antenna,
High-bandwidth interconnects with interposers and fan-out packages
Passive integration with actives
Integrated EMI, heat-spreaders, encapsulation



Power Delivery for Processors

Integrated Power Electronic Component (IPEC)



A) In load (IP, HBM, PIC)
• Monolithic integration
• Hybrid bonding

B) In interposer
• On top side
• Integrated in active interposer
• Embedded in organic interposer

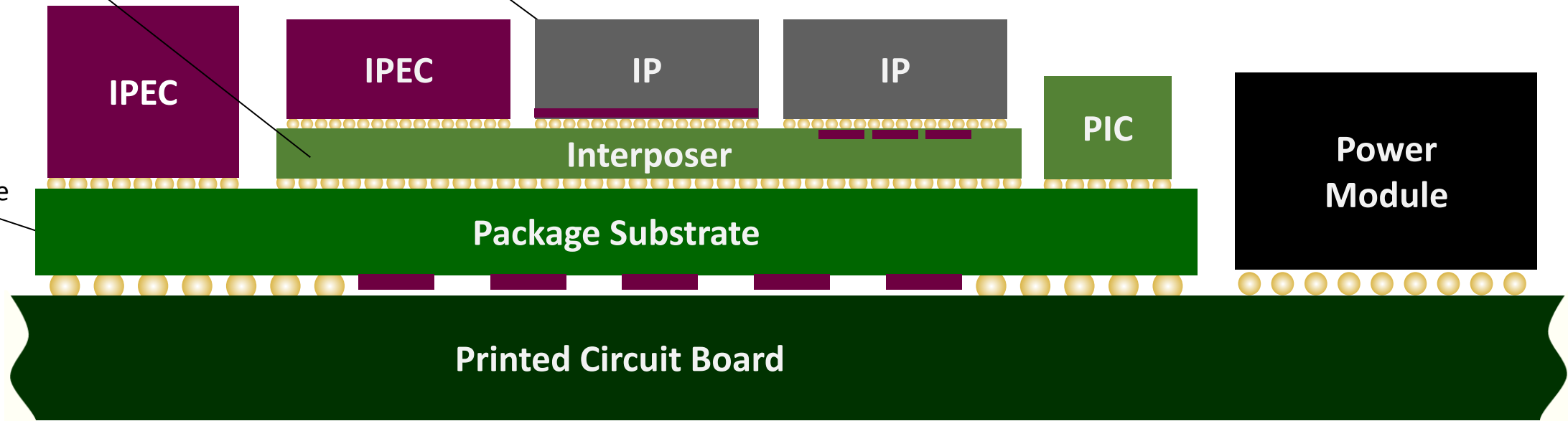
C) In substrate
• On top side
• On land side

Inside SiP

Focus of this presentation

Outside SiP

A parallel initiative



IPECs may be partitioned and integrated in multiple ways, each potentially serving different parts of hybrid topologies

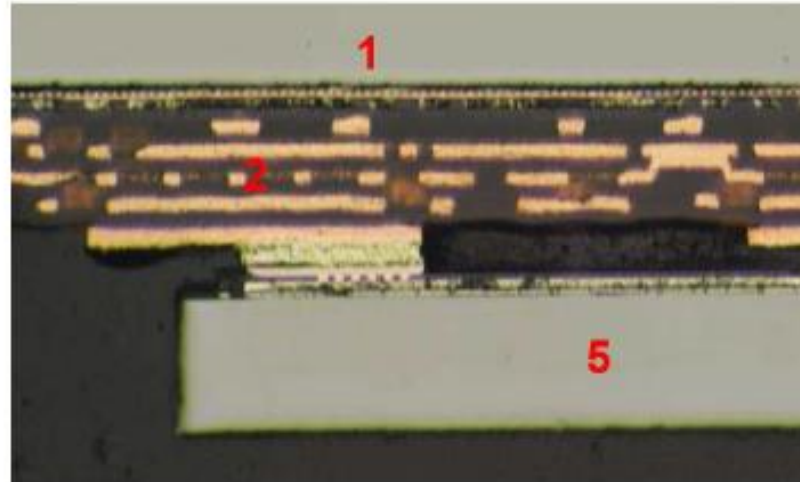
How to Partition the Power Components Around the Load?

Apple iPhone 8 Application Processor/Memory in Fanout (Info) Package

Source: Prismark Partners October 2017



- 13.9 x 14.8mm InFO PoP Package
 - 8% smaller than A10
 - 790 μ m package height
- Memory package with SxS die
 - Die Thickness: 140 μ m
 - 140 μ m EMC thickness over die
 - 3L substrate; 90 μ m thick
 - Underfill between packages
- Processor : ~10 x 8.7mm
 - 30% smaller than A10
 - 150 μ m thick; 15 μ m "top coat"
 - 50 μ m thick, four-metal-layer RDL

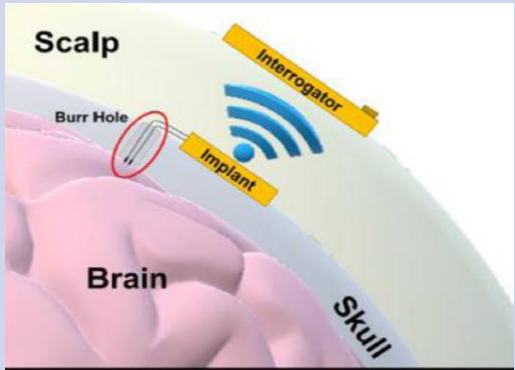


- 1 A11 Die
- 2 RDL
- 3 Vertical Connection
- 4 Memory
- 5 Capacitor

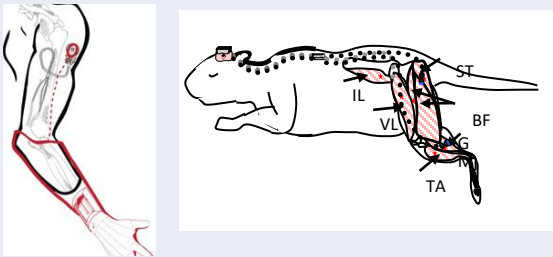
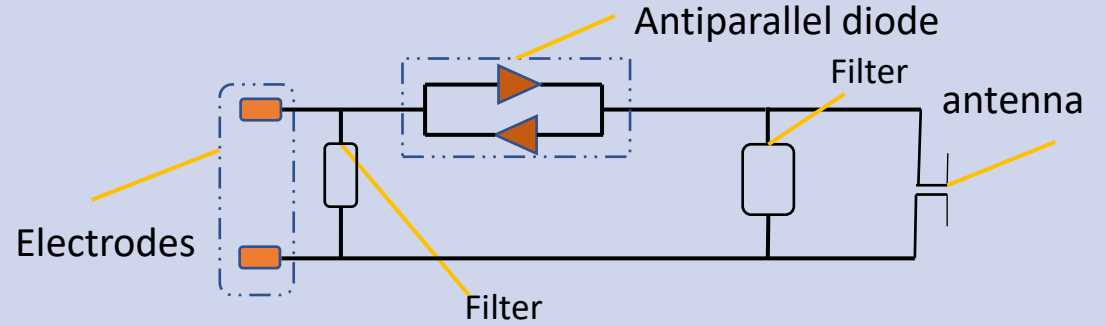


Medical Device Application

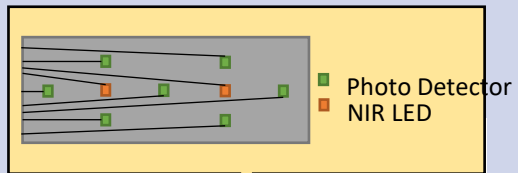
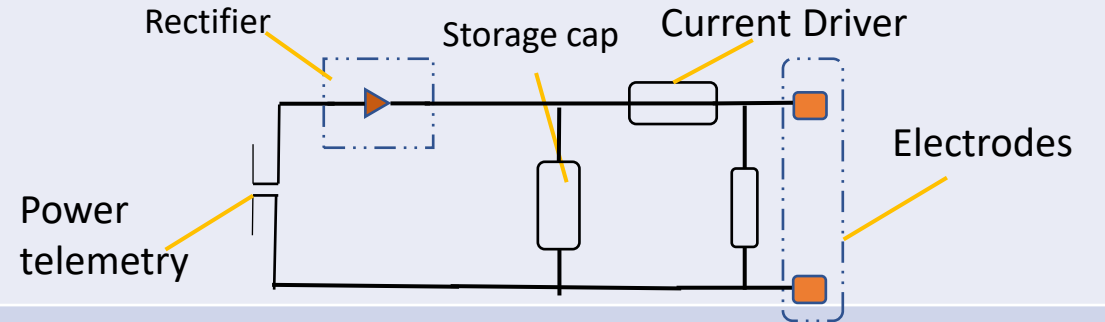
System Description



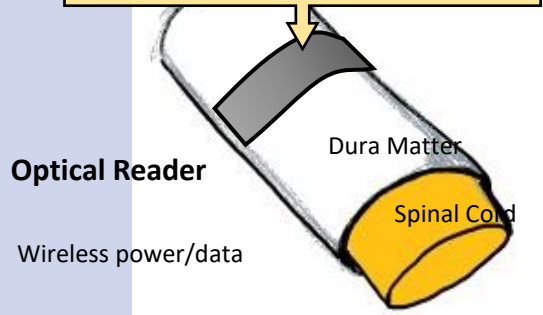
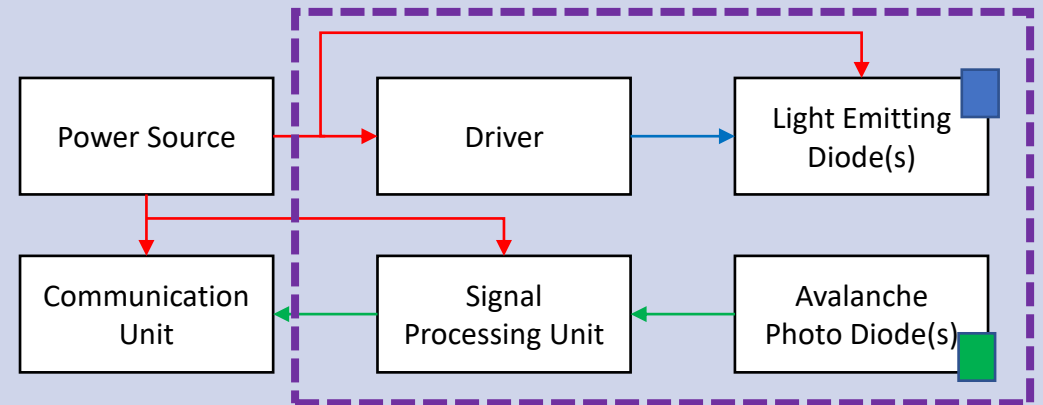
- **Neural recording System:**
- Piezomagnetic antenna to turn on the diode



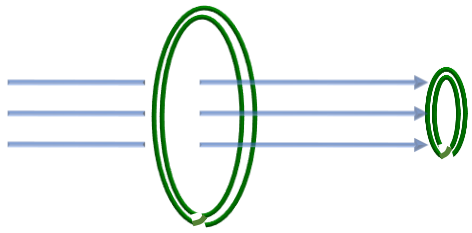
- **Neural stimulation system**
- Piezomagnetic power telemetry to charge the storage capacitor



- **Biophotonic system**
- Piezomagnetic power and data telemetry to power the photonics, drivers and RF interface



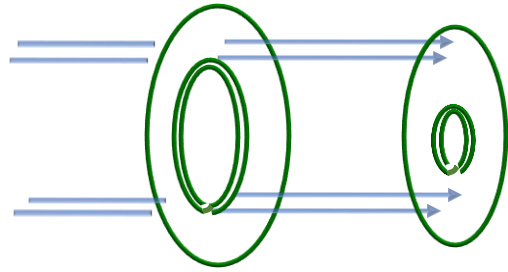
Power Telemetry – Wearable and Implantable



Two-Coil Inductive Link

Receiving coil should be large enough

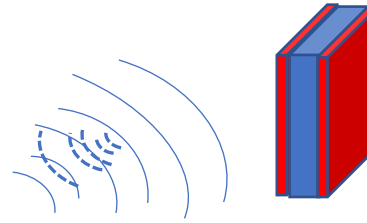
$0.1 - 1 \text{ mW/mm}^2$



Multiple-Coil Inductive Link

Efficiency can be increased with larger separation distance

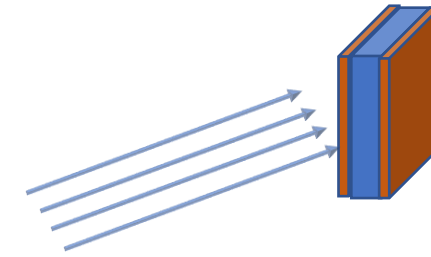
$1 - 5 \text{ mW/mm}^2$



Piezoelectric power telemetry

Receiving link can be reduced to $< 1 \text{ mm}$

$0.1 - 1 \text{ mW/mm}^3$

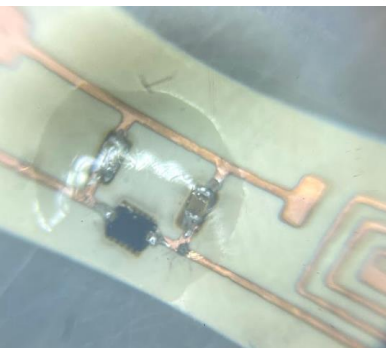


Piezo-magnetostrictive power

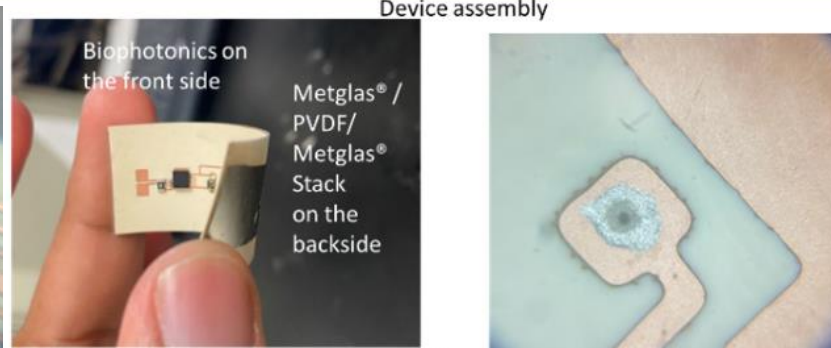
Higher power density can be achieved with smaller sub-mm receivers

$1 - 20 \text{ mW/mm}^3$

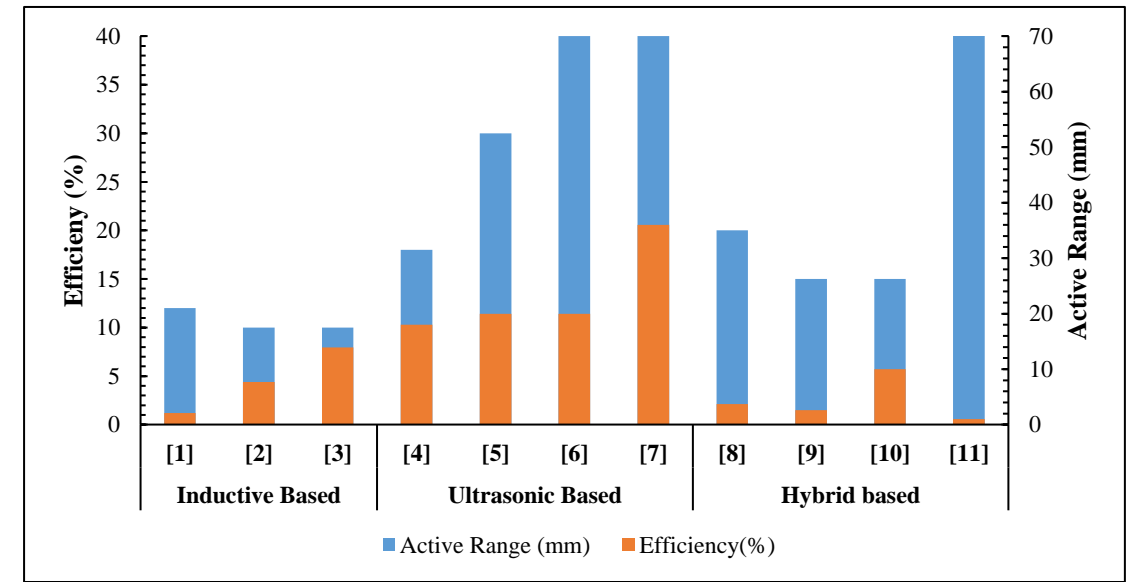
Inductive link



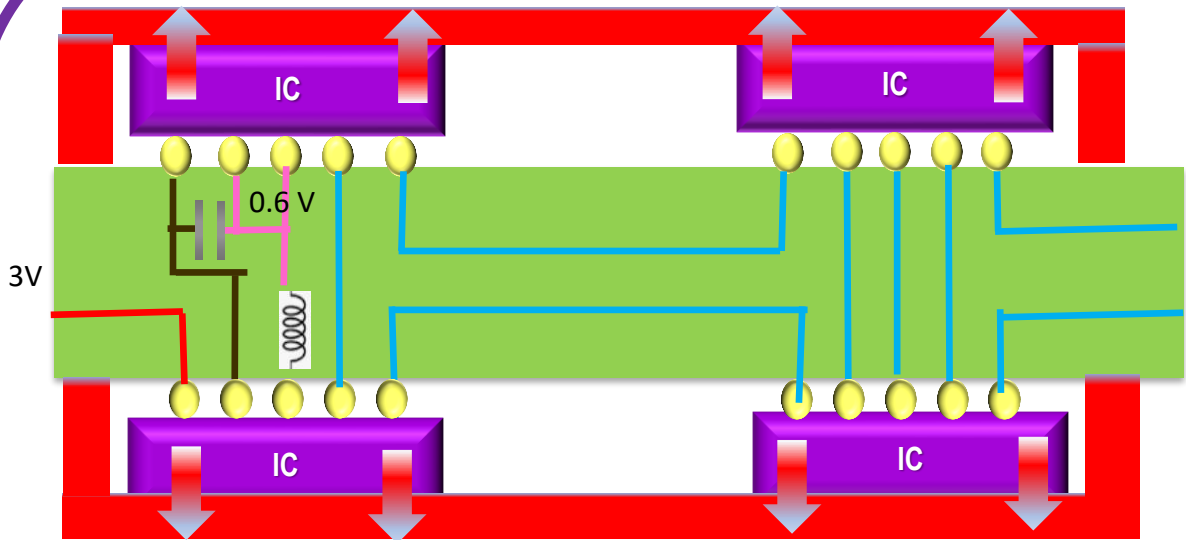
Piezo-magneto



Device assembly



Nanopackaging Drives Future Hardware



Power

Thermal

Reliability

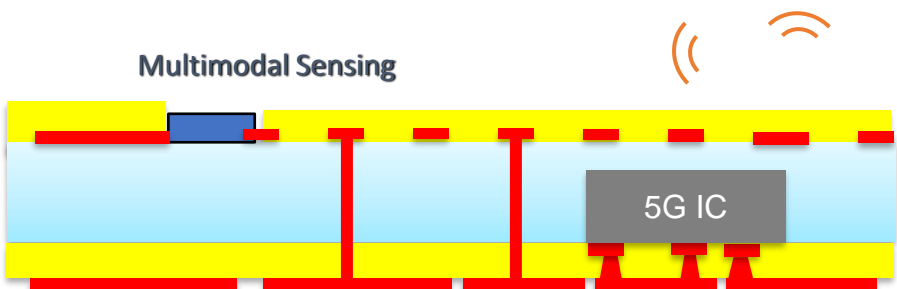
RF

Nanocapcitors and inductors

Cu-Graphene heat-spreaders

**ALD Inorganic films
Humidity barriers**

Nanodielectrics and additive interconnects for 5G and wireless sensors



Multimodal Sensing



5G IC

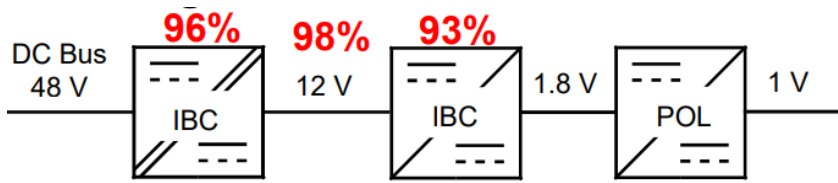
Broadband Wireless Communication

Bioelectronics

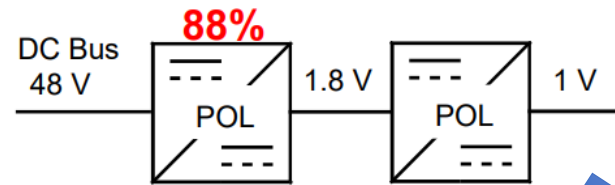
**Electrodes
Power and data telemetry
Storage capacitors
Remateable connectors**



Power Delivery



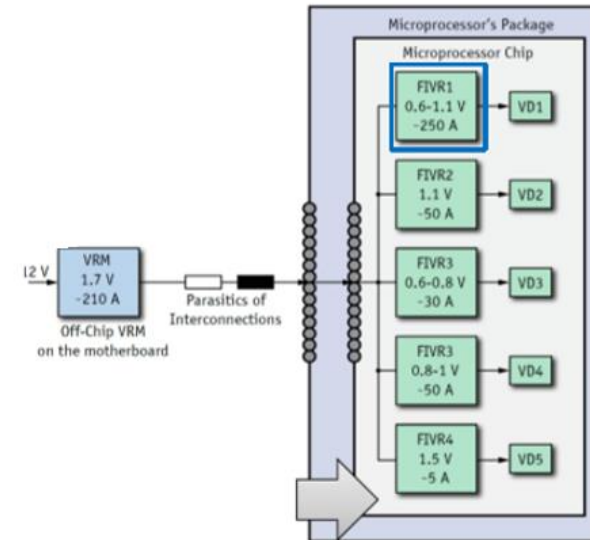
Utilize Advances in:
GaN
CMOS integration
Topologies
Passive components



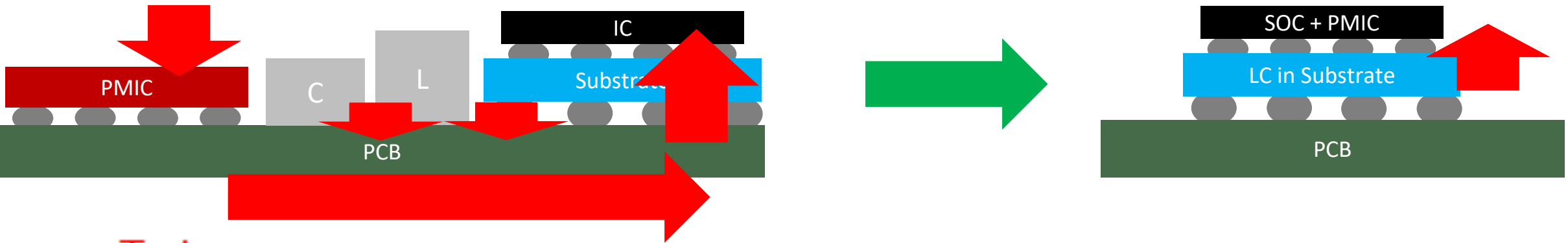
Minimize the stages of power conversion;

Perform power conversion right near the load;

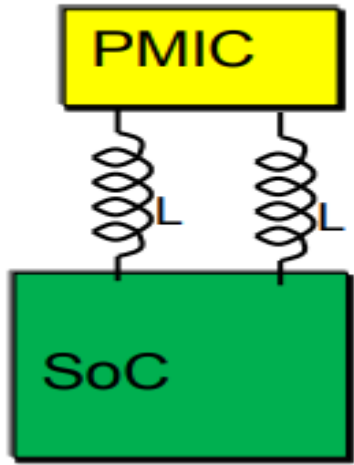
Figures from EPC (Alex Lidow) and IBM Zurich (Arvind Sridhar)



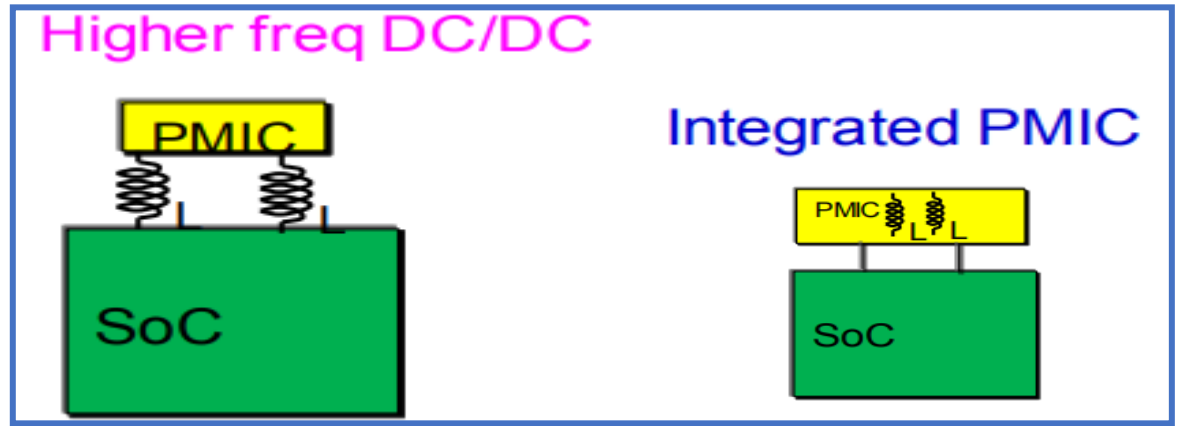
Role of PMIC in Power Delivery



Today



Enabled by advances in magnetics



(Adapted from Indumuni Ranmuthu, PwrSOC 2016 [1])

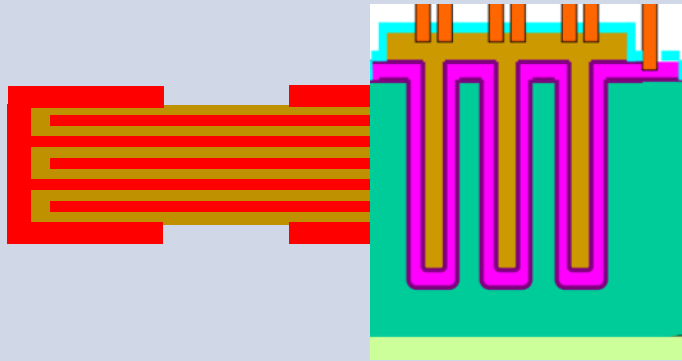
High-frequency power MOSFETS

Advanced Topologies

High-density integrated passives

R&D Needs

Capacitors



Density

High K dielectrics;
Enhance electrode surface area;
New dielectrics and deposition processes

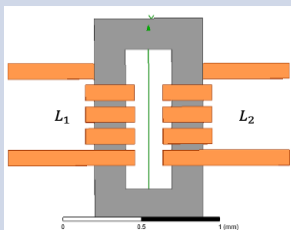
Frequency stability

Electrodes and connectivity with lower parasitics

Integration

Thinner form-factors;
Substrate or wafer or fan-out embedding

Inductors



Density

Higher permeability with saturation field and high resistivity

Efficiency

Low coil DC losses ;
Low core losses with low coercivity and eddy currents

Integration

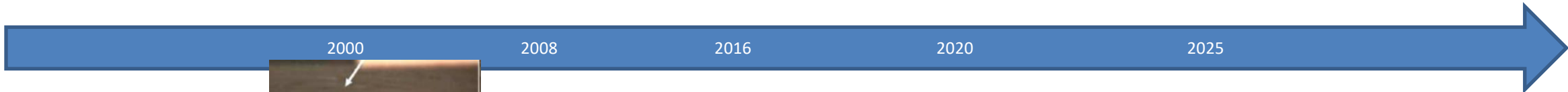
Substrate- or wafer-compatible process

Current-handling

Design innovations;
Scalability in thickness to handle higher current



Embedded Capacitors Roadmap



Board or package embedding; I/O decoupling; 100 MHz

Embedded polymer laminate and dielectrics

0.1 nF/mm² Polymer laminate dielectrics

0.5 nF/mm² Polymer film dielectrics

1 nF/mm²

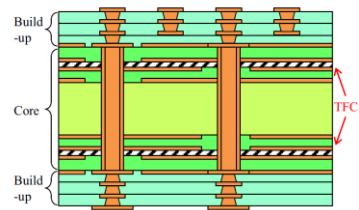


Embedded ceramic film

2-3 nF/mm² Thin oxides

20-30 nF/mm² BaTiO₃ film

30-50 nF/mm² enabled by new multicomponent oxides



Wafer-integrated capacitors

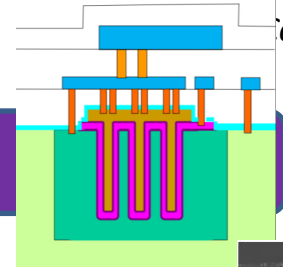
0.08 μF/mm² Silicon capacitors Deep trench

0.25 μF/mm²

0.5 μF/mm²

Ultra-high surface area silicon 1-2 μF/mm²

Multilayered dielectrics on deep trench

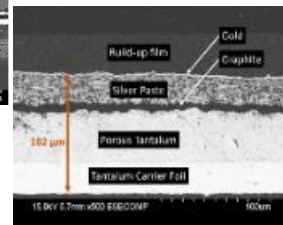
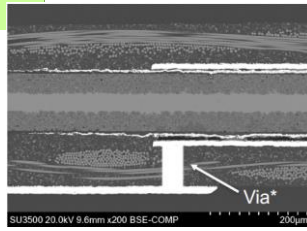


Package embedding; Core and I/O decoupling; 100-500 MHz

Embedded capacitors Panel

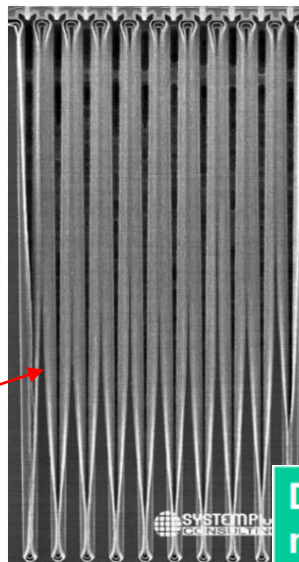
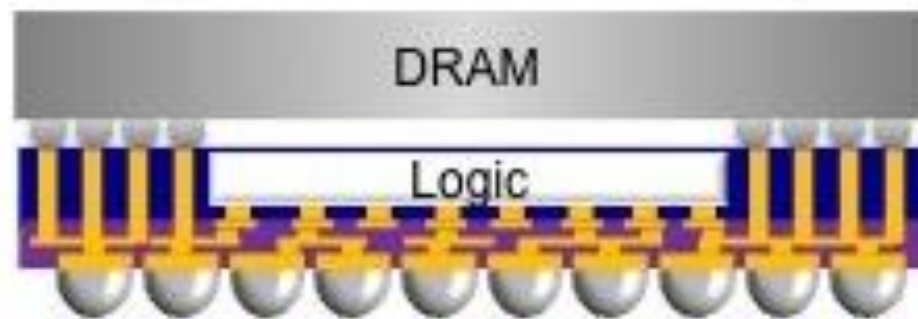
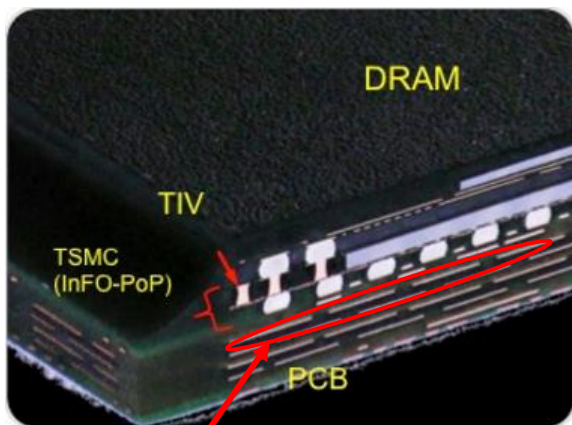
IVR; Embedded PoL 1-20 MHz

Adv. Nanotech. >3 μF/mm²



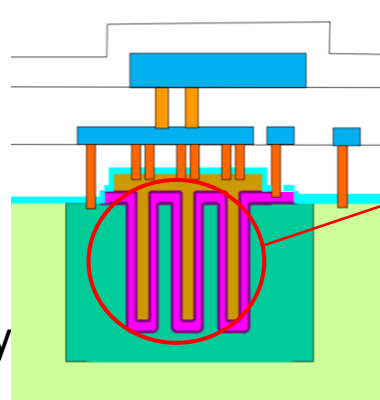
Deep Trench Land-Side Inserted Si Capacitors (TSMC)

Land-side on-Si capacitors for integrated fan-out packaging



- Up to >500 nF/mm² density
- Superior VCC and TCC
- Comparable ESR to MLCCs
- Thickness as low as 100 μm

1 × 0.5 mm footprint
 Located underneath info-POP supported by extra PCB layer



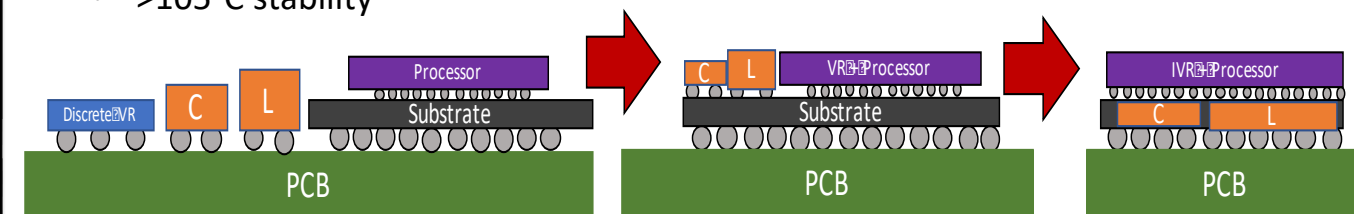
Deep trench capacitor structure

Density, nF/mm ²	Breakdown Voltage, V	TDDB, V	Max Voltage rating, V
180	16.1	7.0	4.5
250	14.3	6.8	4.2
500	6.5	4.5	3.2
600-700	4.0	3.8	2.5-1.2

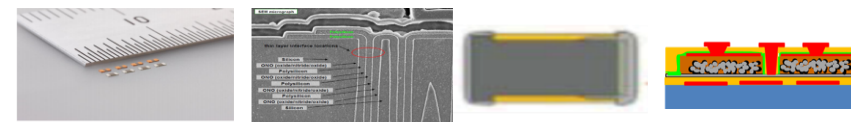
High-Density Capacitors for Integrated Voltage Regulators

Objectives

- Ultra-high density capacitors:
 - $>1 \mu\text{F}/\text{mm}^2$ at 1 MHz, 3-48 V, & 50 m Ω ESR
 - 1 nA/ μF leakage current
 - Simpler processing on wafer or package
 - 100 μm thickness
 - $>105^\circ\text{C}$ stability

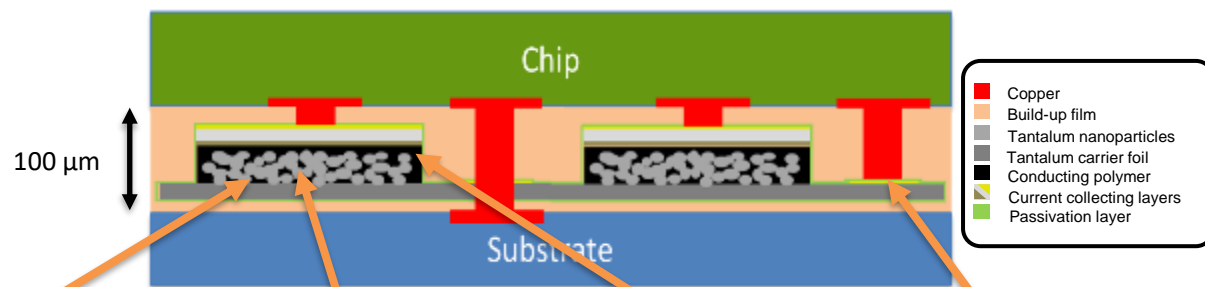


Prior Art



	MLCC	Trench Caps	Ta Chip	Emerging Need
Volumetric Density	20 $\mu\text{F}/\text{mm}^3$	1 $\mu\text{F}/\text{mm}^3$	$\sim 10 \mu\text{F}/\text{mm}^3$	50-100 $\mu\text{F}/\text{mm}^3$
Thickness	100 μm	100 μm	600 μm	50-100 μm
Freq. Stability	10-100 MHz	>1 -10 MHz	0.2 -1 MHz	>10 MHz
ESR	~ 10 m Ω	50 m Ω x μF	>100 m Ω x μF	~ 50 m Ω x μF
% $\Delta\text{C}/\text{V}$	-13 % to -70% (1 to 4 V)	~ 0 %	~ 0 %	~ 0 %
Max. Temp	85 $^\circ\text{C}$	150 $^\circ\text{C}$	125 $^\circ\text{C}$	$>125^\circ\text{C}$
	PICK AND PLACE			FILM EMBEDDING WAFER OR PANEL INTERCONNECTS

Unique Approach



Printed Tantalum Nanoparticles Anode

- High-surface area at ultra-thin form-factor
- Scalable to any design need

Nanoscale Ta₂O₅ Dielectric

- Paraelectric for DC bias and temperature stability
- Amorphous for low leakage current

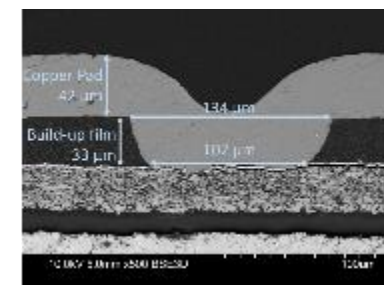
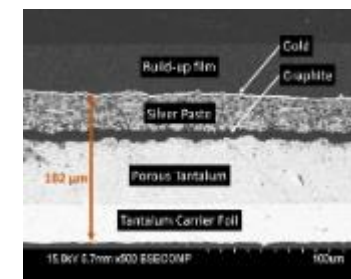
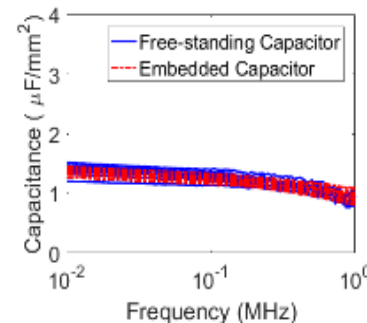
Conformal Conducting Polymer Cathode

- Low-resistivity and thick coating for low ESR
- Self-healing for low leakage current

Foil-transfer integration

- Thin-film lamination
- Ultra-short copper interconnections for reduced impedance
- Low-cost, panel-scale, 3D approach

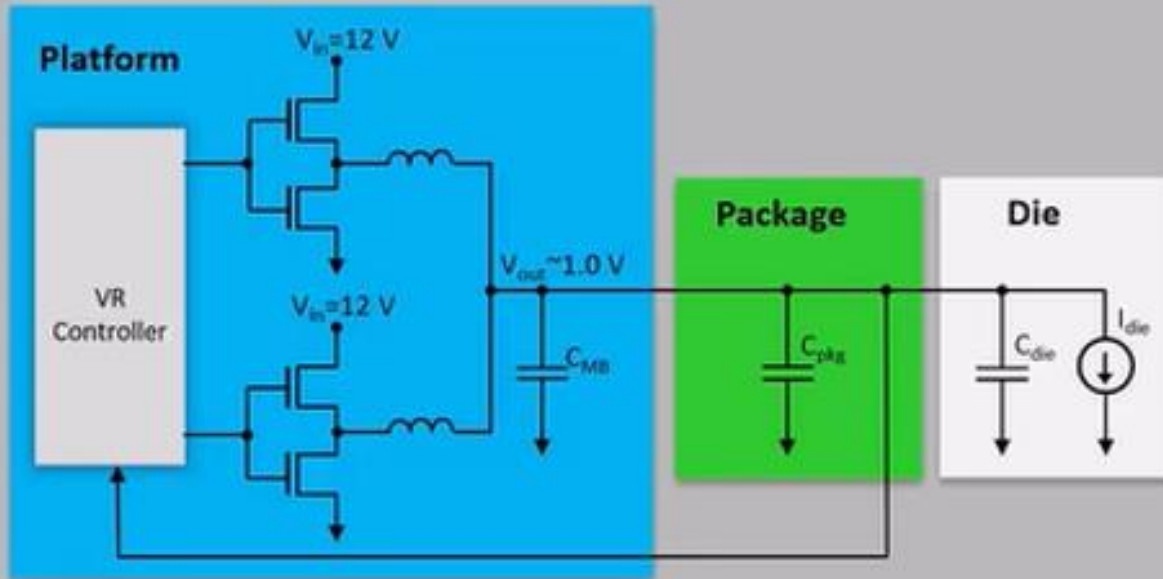
Major Accomplishments



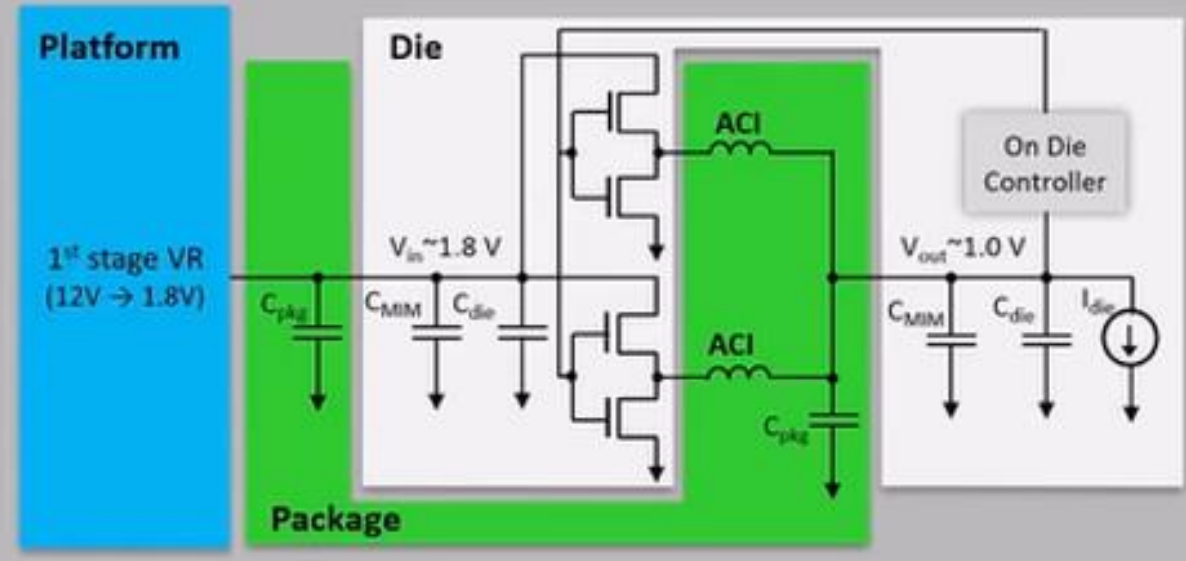
$>1 \mu\text{F}/\text{mm}^2$ up to 1 MHz at 5 V with low ESR, low leakage current, and 100 μm component thickness

Integrated Power Delivery in the Package Key for High-Performance in Computing

MBVR (3rd Generation Intel® Core™ Processor)



FIVR (4th Generation Intel® Core™ Processor)



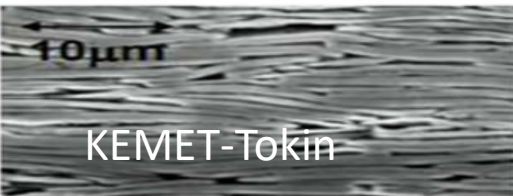

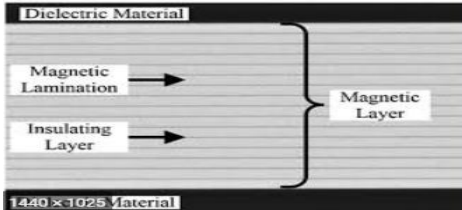
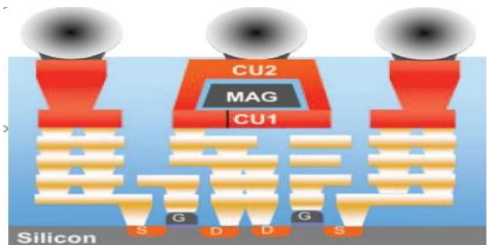
Previously Voltage regulator is designed on the PCB

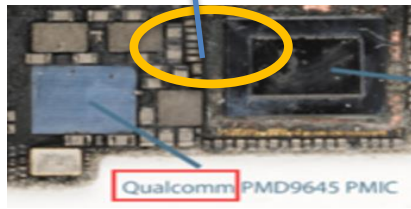
Few filter capacitors in package

Now, Voltage regulator is moving into the package

More filter capacitors moving into the package

Inductor Technologies

	Discrete (Ferrite or Metal powder)	Magnetic composites –substrate- embedding	Nanomagnetic films: On-chip	Need
L/Rdc nH/milliohm	15-25	5-10	0.1-0.2	>>10
Q	>20	<10	5	>20
Current-handling A/mm2 Thickness	0.01 – 0.1 200- 500 microns	0.1 – 1 50 - 200 microns	5-10 A/mm2 25 microns	5-10 A/mm2 25-50 microns core
Cost	Low	Low	High	Low
	<p>Discrete (Ex.0.5 x 0.1 x 0.5 m)</p>   <p>KEMET-Tokin</p> <p>Nitto Denko Magnetic film Copper winding Magnetic film Laminate substrate</p> <p>Substrate-embedded inductors Magnetic Core (0.5 - 0.6 mm)</p>	  <p>Dielectric Material</p> <p>Magnetic Lamination</p> <p>Insulating Layer</p> <p>Magnetic Layer</p> <p>1440 x 1025 Material</p> <p>Intel and Ferric</p>		



Prior Art- Inductor Integration

Fe

On-Chip IVR

Monolithic integration

Magnetic-core inductor

CoZrTaB

Ms: 1.5 T

Hc: 0.39 Oe

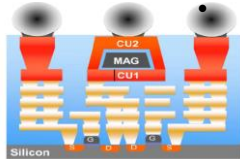
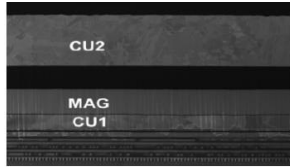
Switching frequency

80 to 100 MHz

Inductance

300 nH/mm²

- Peak Q Factor > 20 @ ~100MHz
- Peak Inductance Density ~300nH/mm²
- L/RDC >200nH/Ω for L > 100nH
- L/RDC of 120nH/Ω for L ~ 10nH
- Current Density exceeding 12A/mm² for coupled inductors
- Saturation Current exceeding 1.5A for single inductors
- Cross wafer inductance variability $\sigma < 3\%$
- Other Devices in development: Transformers, improved inductor designs



On-Chip IVR

Monolithic integration

Magnetic-core inductor

• Ni₄₅Fe₅₅

• Ms: 1.6 T

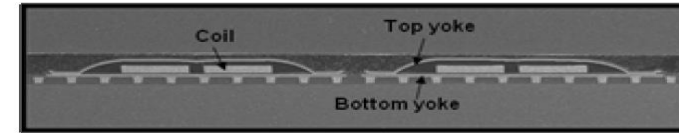
• Hc: 0.2 Oe

Switching frequency

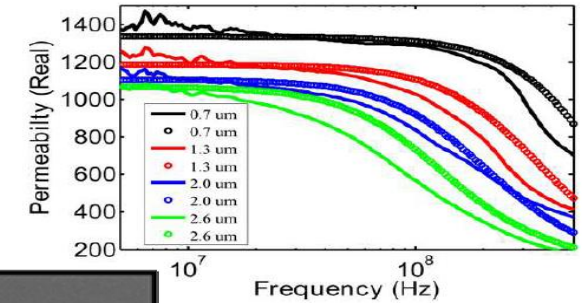
• 50 to 200 MHz

Inductance

• 130 nH/mm²



IBM

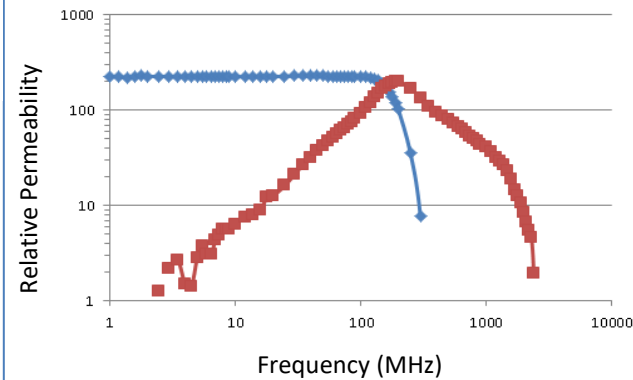
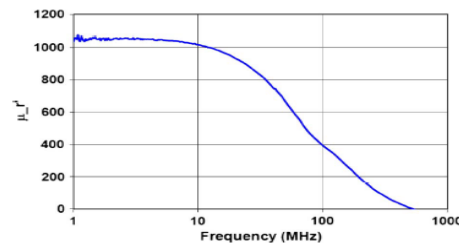
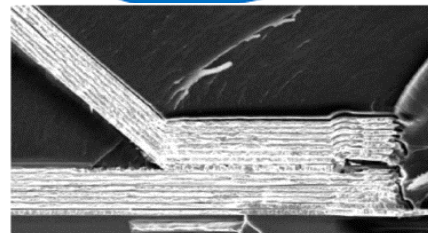


On-Chip

Monolithic integration

- Magnetic-core inductor
 - Ni₈₀Fe₂₀
- Switching frequency
 - 30 MHz to 140 MHz
- Inductance
 - 17 nH
- 16 inductors in 2.8 mm²
 - Inductor size: 0.17 mm²
- Current: 1.5 A




intel



- Material sample thickness = >40μm
- High deposition rate – high throughput and low cost
- IC or glass substrate- compatible
- Deposition thickness capability up to 50μm
- $\mu_r = 200$, $B_{sat} = 1.3$ T, $Q @ 5$ MHz > 90, $Q @ 20$ MHz = 30
- 0.5 microhenries; I_{sat} of 2 Amp on 6 inch;
- Toroid and solenoid inductors

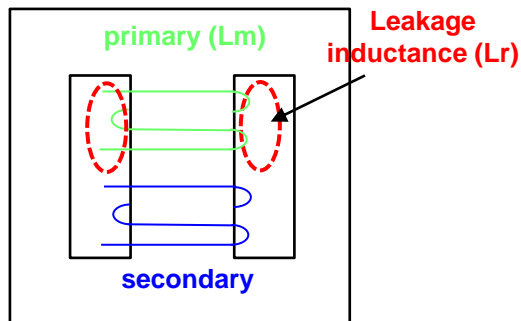
Magnetic Components: Integration

- Planar transformers with windings implemented on PCB are gaining momentum in R&D and production

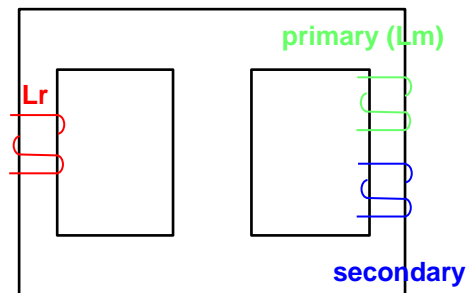
Component	Method	Conventional Wire-wound	Wire-wound integrated	PCB winding planar core
Structure		 [1]	 [2]	 [3]
Power		3.3kW	192W	5 kW
Profile		> 45 mm	> 30 mm	20 mm
Leakage inductor		Discrete	Integrated	Integrated
Process		Manual (Litz wire)	Manual (Litz wire)	Thick Cu PCB
Repeatability		Low	Low	High

- Monolithic integration of transformer and inductors on single core to minimize part count

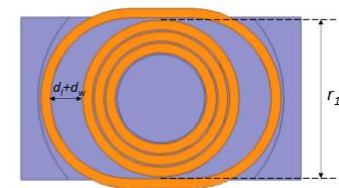
Transformer + inductor



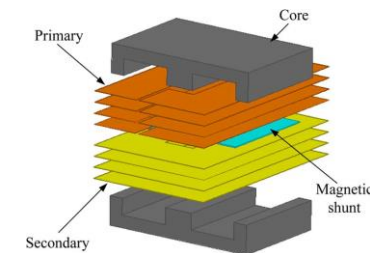
Additional winding



Air gap control



Magnetic shunt insertion



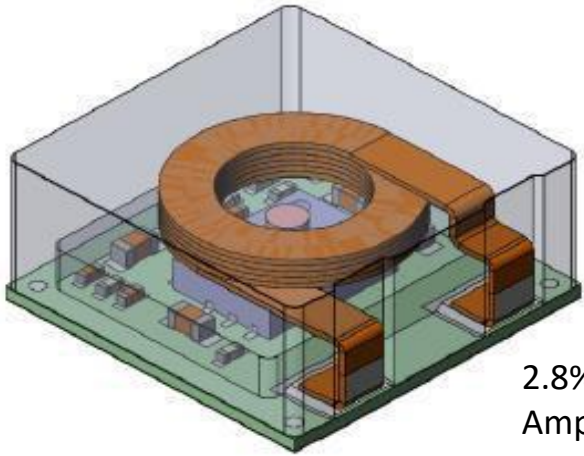
Source: Virginia Tech, APEC 2015

Source: NUI Galway

Medium Frequency – Medium Power: Inductor Advances



PSI2: Inductor in package molding

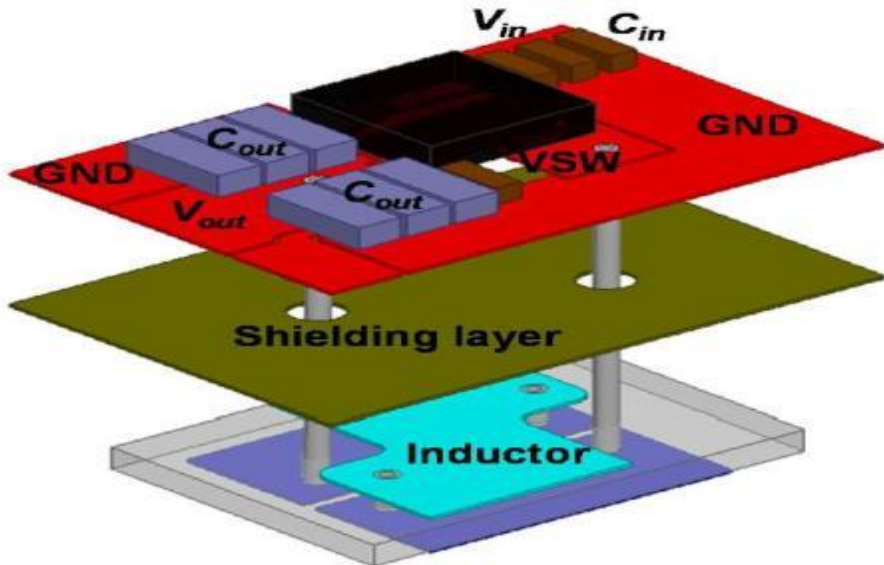


Better thermal, shielding,

High current-handling and efficiency

2.8% increase in efficiency with 3-5 Amp current

Virginia Tech: Inductor in PCB Substrate

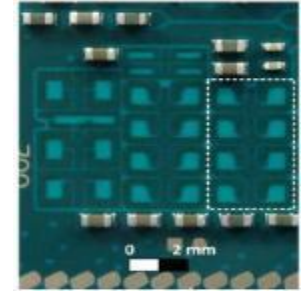


PCB-embedded ferrite and metal flake composites

Package IVR: Integrated Voltage Regulator

Inductors integrated in substrates

- Air-core inductors
- Multiple domains
 - High-current: >20 A
 - Medium-current: 5-20 A
 - Low-current: <5 A
- Switching frequency: 140 MHz



TAIYO YUDEN

Inductor in package

Ferrite type
4.0mm×4.0mm×1.2mm
16mm²
NRS4012T1R0NDGG



MCOIL™
2.5mm×2.0mm×1.2mm
5mm²
MAMK2520T1R0

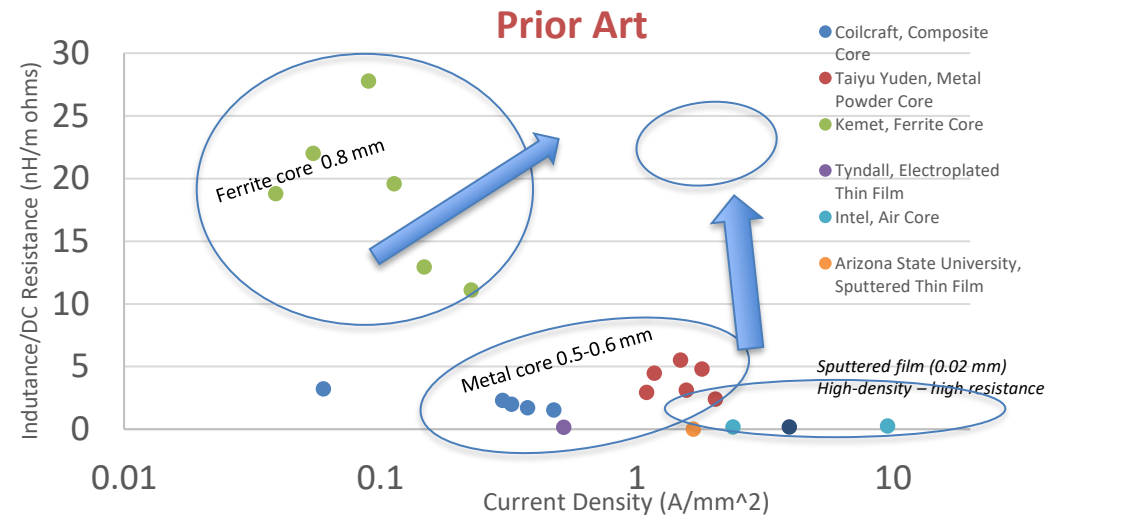
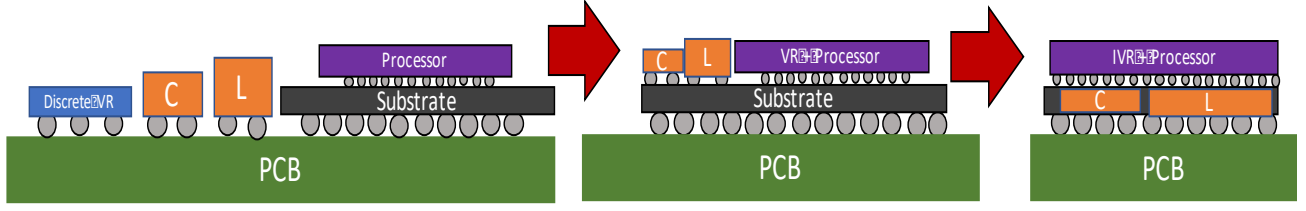
4X increase in current-handling with metal compacts compared to ferrites

High-Density Embedded Inductors for Integrated Voltage Regulators

- Embedded inductors for power converters:

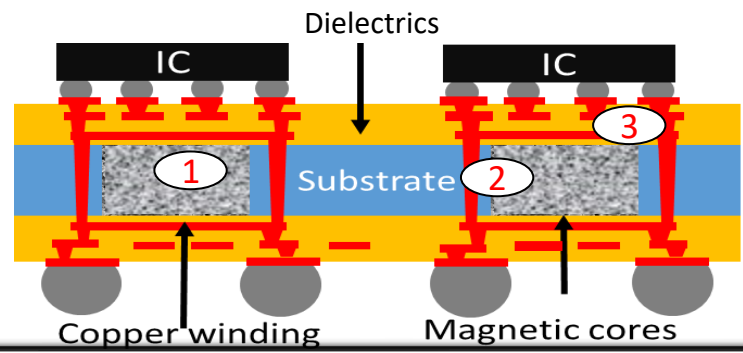
Objectives

Target
 20 nH/milliohm
 2 A/mm²
 20-50 microns



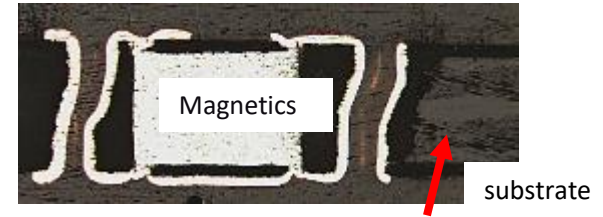
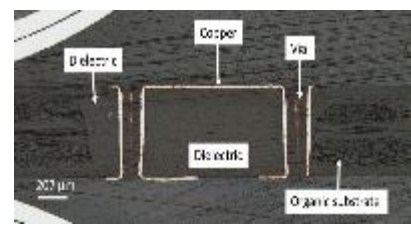
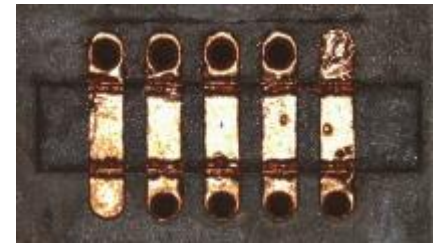
Unique Approach

- Substrate-compatible magnetic composites with high permeability
 - High permeability for high-inductance density
- Embedded solenoid inductors
 - Embedding for miniaturization
 - Design for high-current density
- Substrate design rules to fabricate thick copper
 - Low resistance



Major Accomplishments

- Embedding of high current density and high-efficiency inductors embedded in organic substrates. Current status:
 - Thickness: 500 um
 - Inductance: 8nH/mm²,
 - Current: Projected to 1 A/mm²
 - Resistance: projected to <10 m Ω



3D Power Packaging

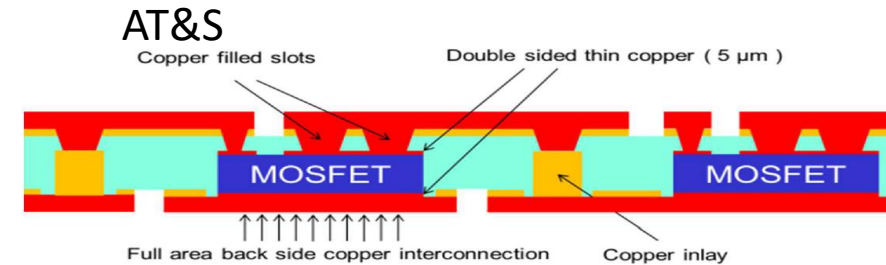
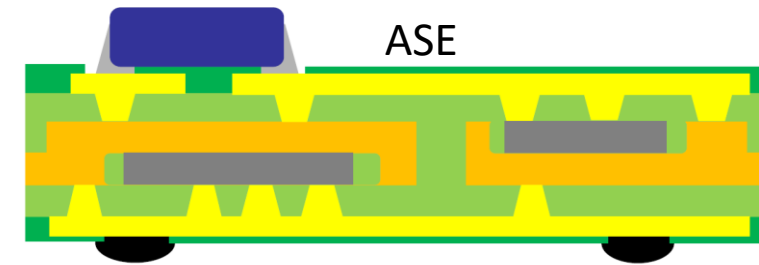
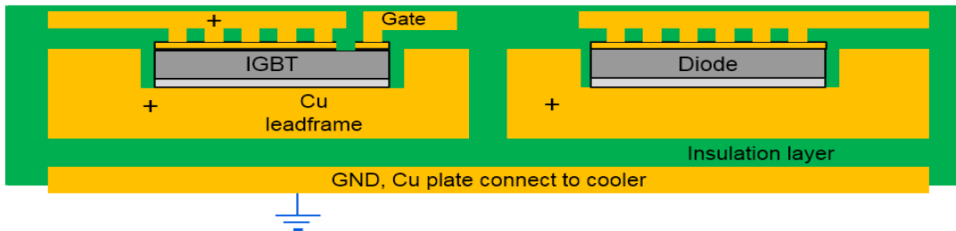
- Multiphysics converter design (topology & hardware co-design)
- Advanced GaN devices & high-temp passives

- Structure and process innovations
- Doubleside wafer plating
- Panel-scale embedding of power devices
- High-temperature materials with enhanced interfaces for Hi-Rel

Infineon



Schweizer

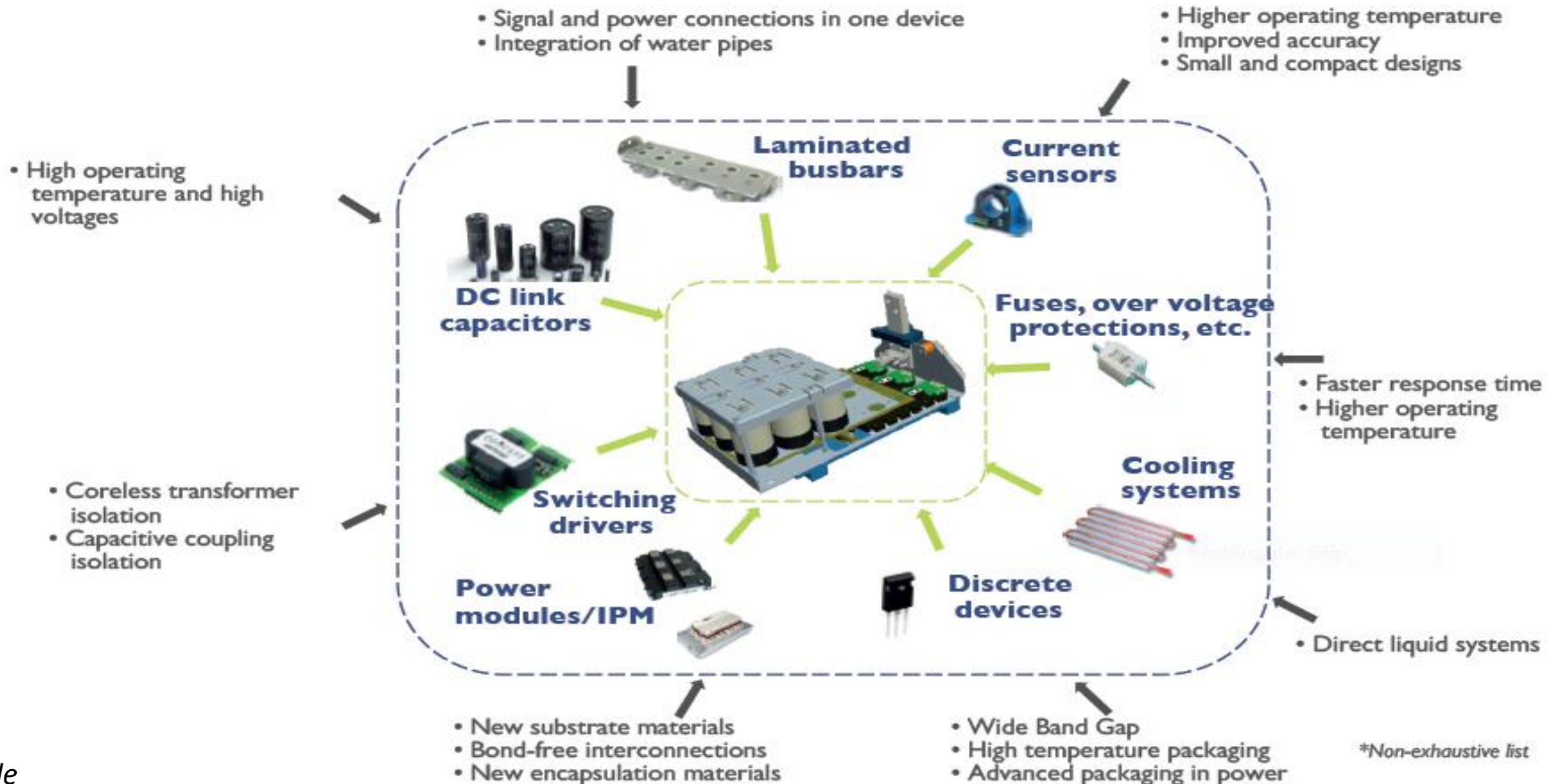


- Sintered copper interconnections between devices, IMS or leadframe and PCB
- Barriers for oxygen and moisture
- Advanced encapsulants

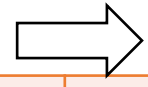
- Advanced cooling loop with temp uniformity
- System-level thermomechanical and electrical reliability:



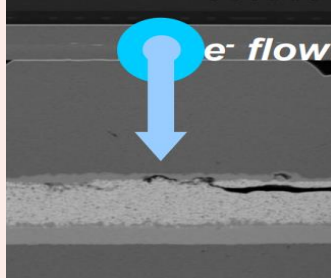
Improvement trends* for different system components



Evolution of Die-Attach Materials

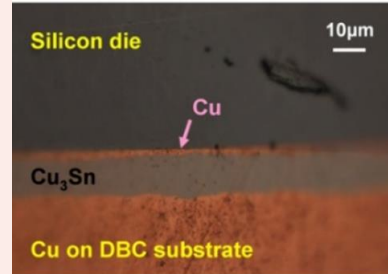


High-lead solders



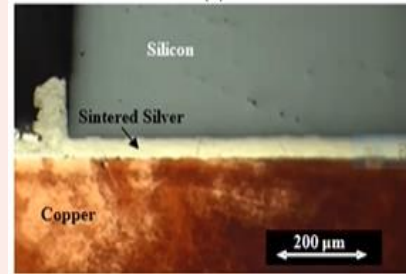
Koduri, Texas Instruments
Current is not needed for lateral GaN die-attach)

Transient Liquid Phase Sintering



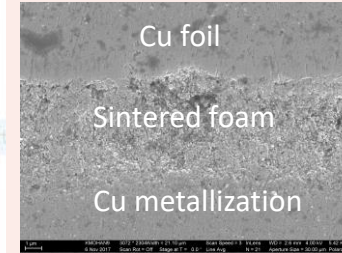
Infineon

Nanosilver



Jiang Li (TI, Virginia Tech)

Nanocopper



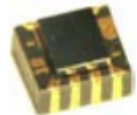
Vanessa Smet, Georgia Tech

Nanocopper-microwire-graphene multilayers

	High-lead solders	Transient Liquid Phase Sintering	Nanosilver	Nanocopper	Nanocopper-microwire-graphene multilayers
Pressureless assembly capability	Pressureless		Requires pressure	Requires more pressure	Pressureless with reactive nanosurfaces
Electrical and thermomechanical reliability performance	Moderate with low homologous temperature	Moderate with Kirkendall voids	Microstructural instabilities and diffusion	Die shear strength is low with smooth backside metallization	
Safety	Lead-based				
Cost			High	Moderate	Low, because of design and process flexibility

Low Power (Consumer Electronics) to High Power

1.2W , 900W/in³



2MHz

Micro power module

Consumer

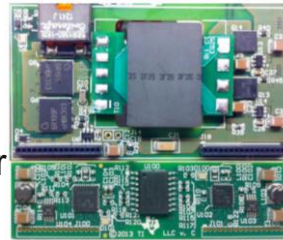
10W , 350W/in³



780kHz

Step down converter

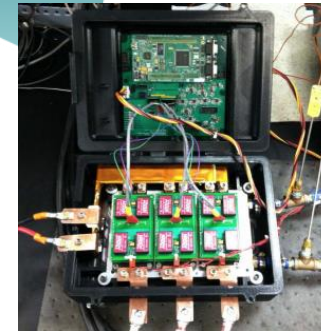
500W , 308W/in³



GaN DC-DC converter

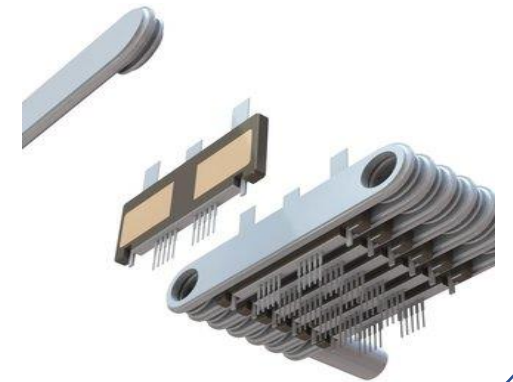
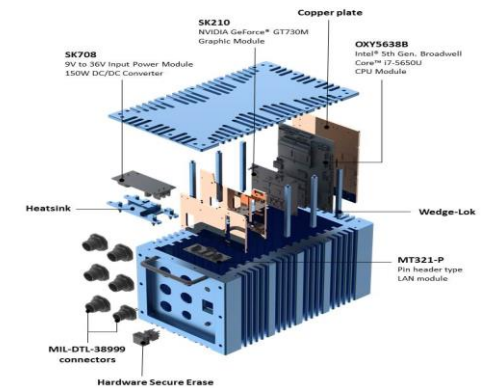
- Higher frequencies
- Higher power densities
- More integration
- Single package solutions

30kW , 81W/in³


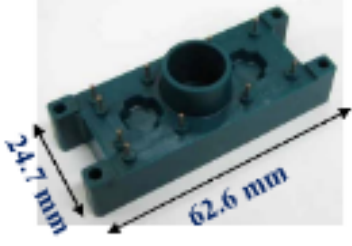
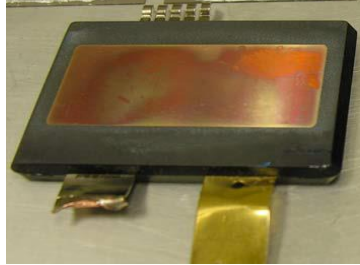
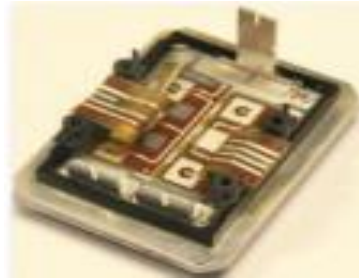
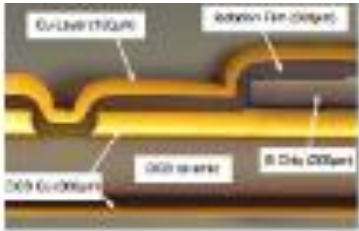
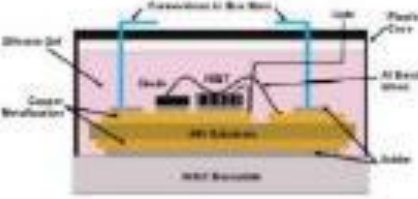
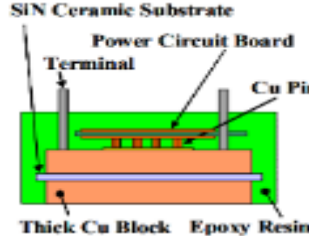
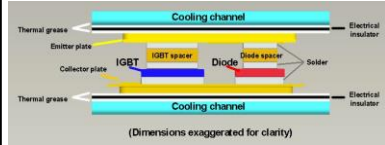
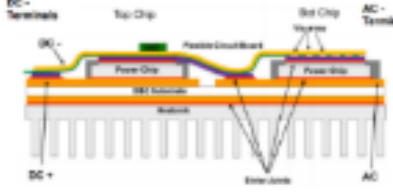



30kW all SiC inverter

High Power



High-Power Packages – Leading-edge Products

Package	Standard wire bond package	Cu pin interconnect w/ thick Cu DBC	Double-sided liquid cooling	Cu traces on flexible foil w/ sintered joints	Planar interconnect using Cu plating
	Conventional	Fuji Electric	Denso	Semikron SKiN	Siemens SiPLIT
Package structure					
Cross-section					
Parasitic inductance					
Thermo-mechanical					
Note	<ul style="list-style-type: none"> • Wire bond • Solder die attach 	<ul style="list-style-type: none"> • Cu pin joints • Gel replaced with epoxy 	<ul style="list-style-type: none"> • Double sided cooling • Double DBC 	<ul style="list-style-type: none"> • FPCB Gate drive integrated • Ag sintered joints 	<ul style="list-style-type: none"> • Area joints by Cu electroplating

Not Available

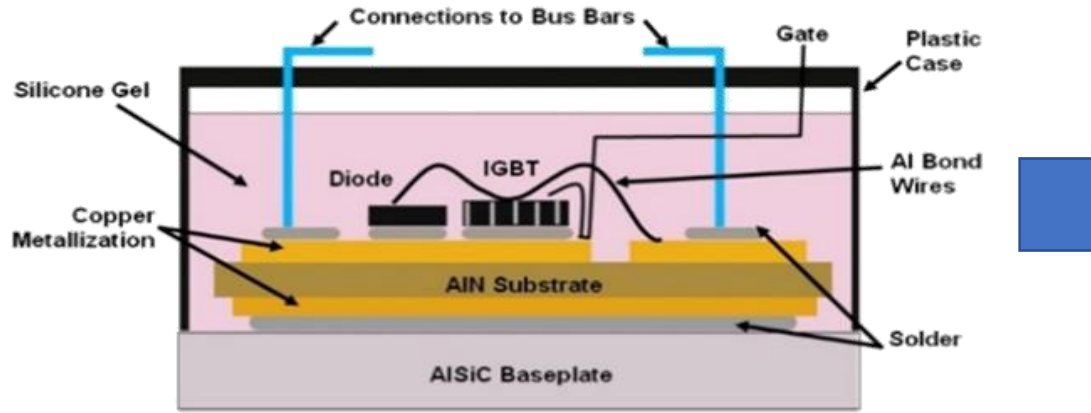
Very bad

Bad

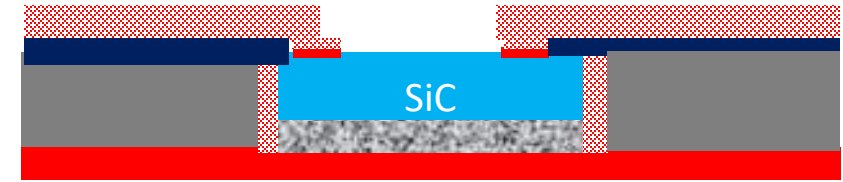
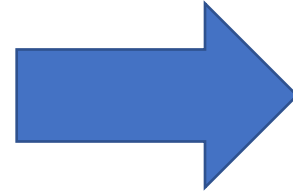
Good

Very Good

Traditional to 3D Power Packaging

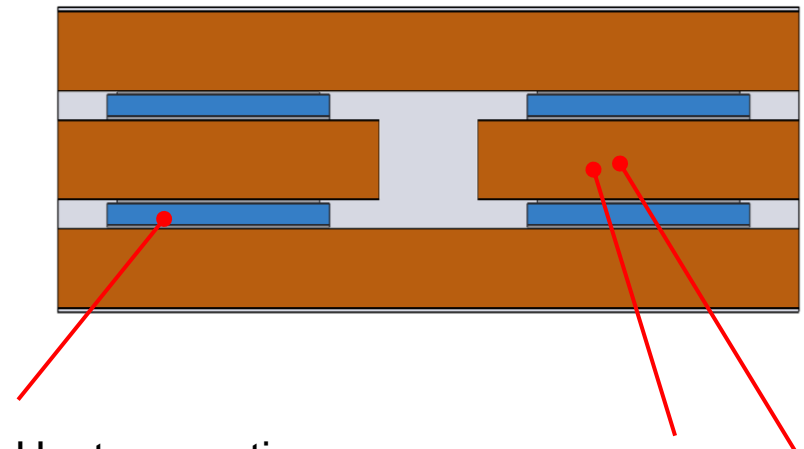
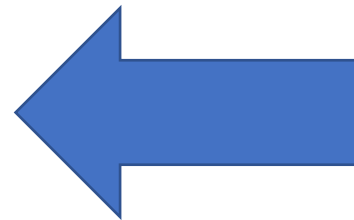
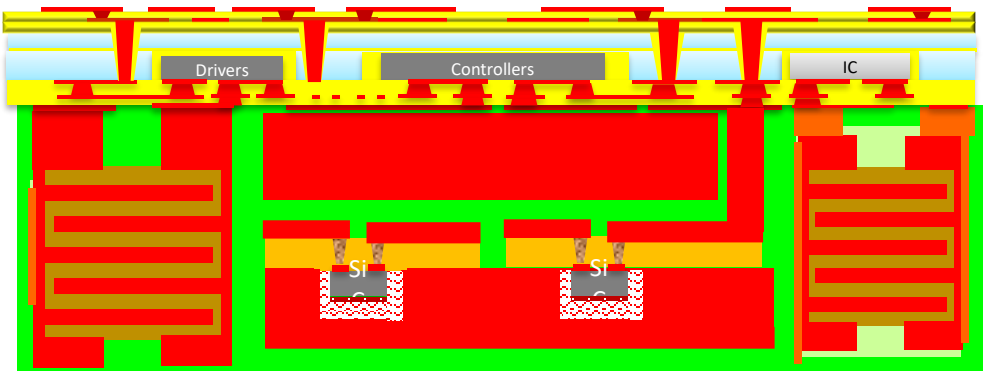


- Reliability challenges with nanocopper and nanosilver
- Thick packages
- Large electrical inductance and high thermal resistance



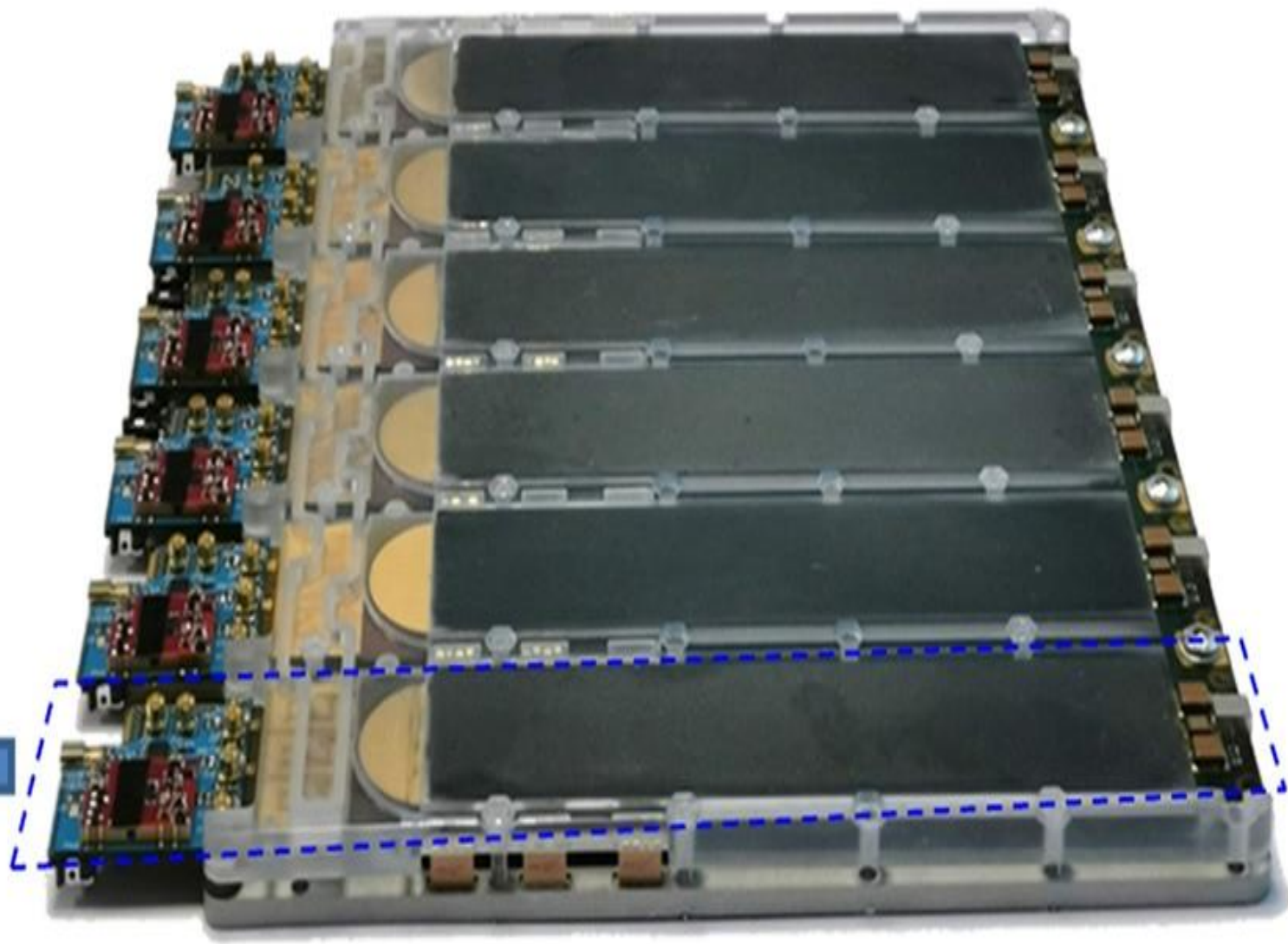
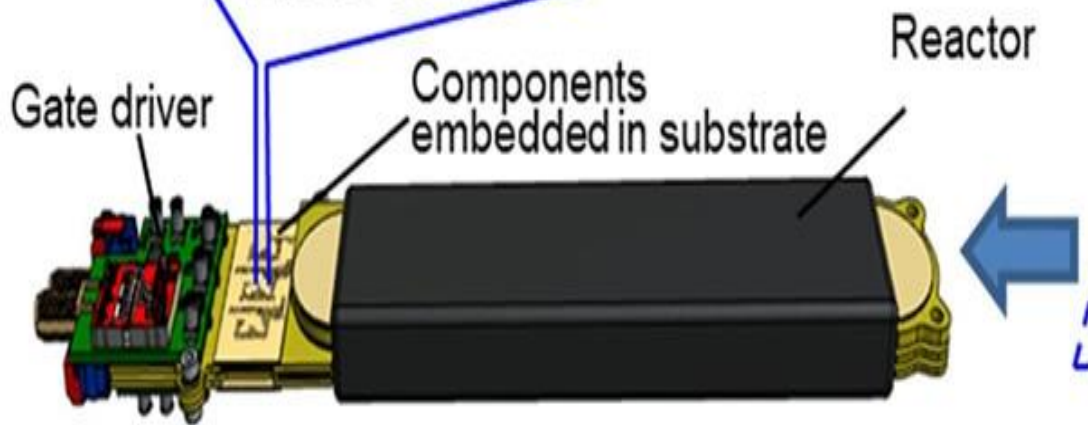
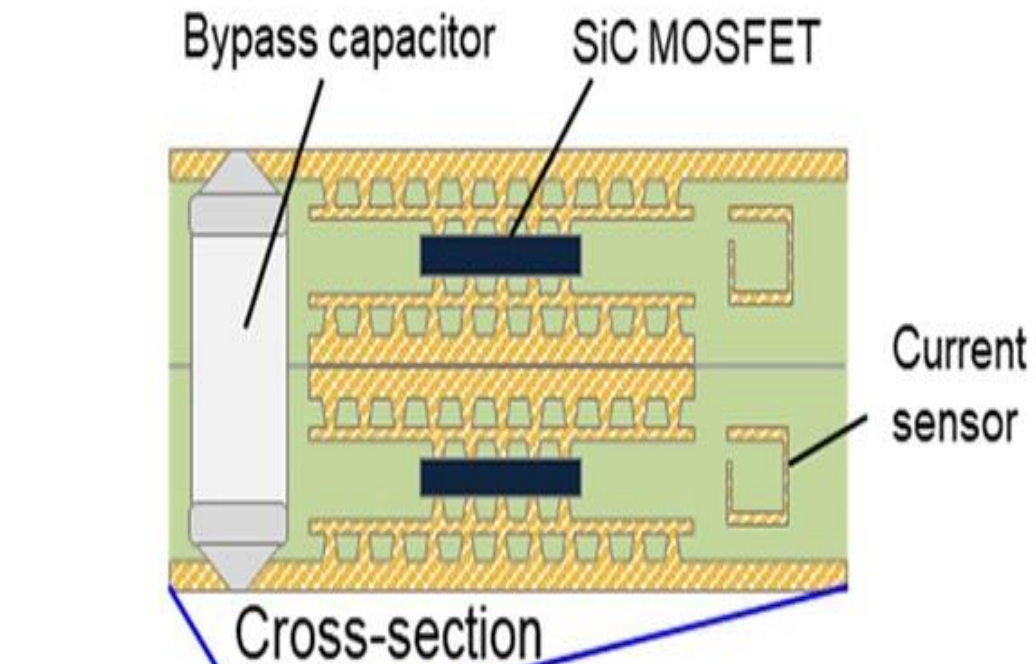
Leadframe Fan-Out Packaging

- No reliability challenges with nanocopper
- (Bonding layers are in compression)
- Thin packages
- Lower electrical inductance and thermal resistance

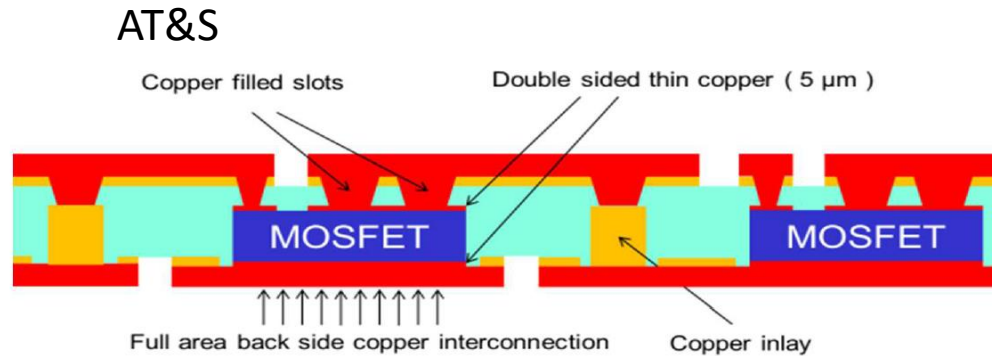


Heat generation
100 W

Heat transfer coefficient
10,000~50,000 W/m²K

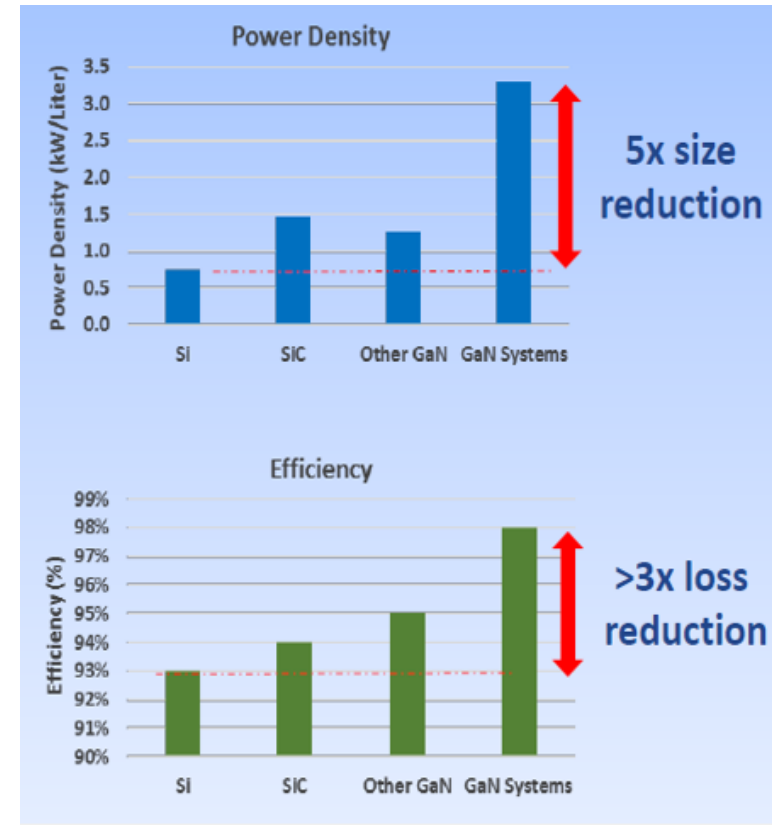


3D Power Packaging: AT&S and GaN Systems



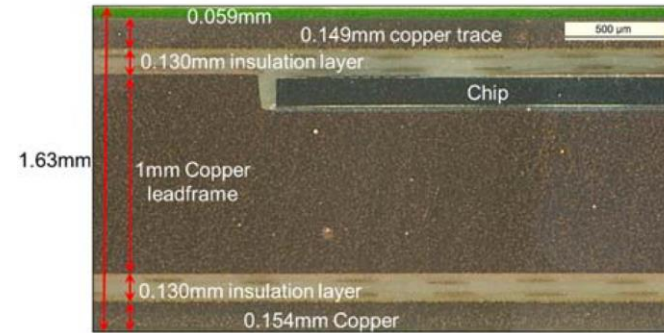
- Planar Surface-embedded components (PARSEC)
- 250-450 V; 200 A: 50 kW inverter
- IMS PCB with thermal-conducting prepregs
- Better partitioning, faster switching, reduced switching losses

GaN Systems 7 KW, Level 2 EV Charger



3D Power Packaging - Schweizer

- Thick lead-frame heat-spreader with cavity for die placement
- Laser-drilled and plated-vias for top interconnect on top side (logic integration possible)
- Power embedded PCB offers improved electrical, thermal performance with increased power density



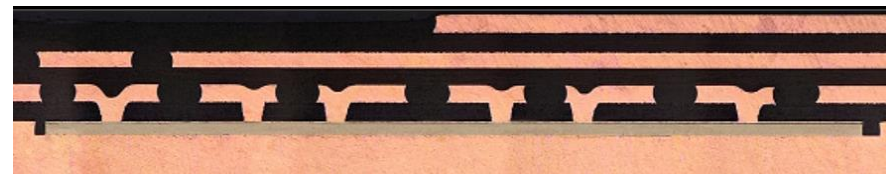
Kearney et al., ABB
Corporate research

- Improved switching behavior
- Reduced losses
- Optimized heat dissipation
- Control & power co-integration

P2Pack Half-bridge with embedded shunt:

- No die-attach reliability concerns
- Laminate temp: 175-220 C
- 38% reduction in losses for power PCB
 - Over 100-500 Amp

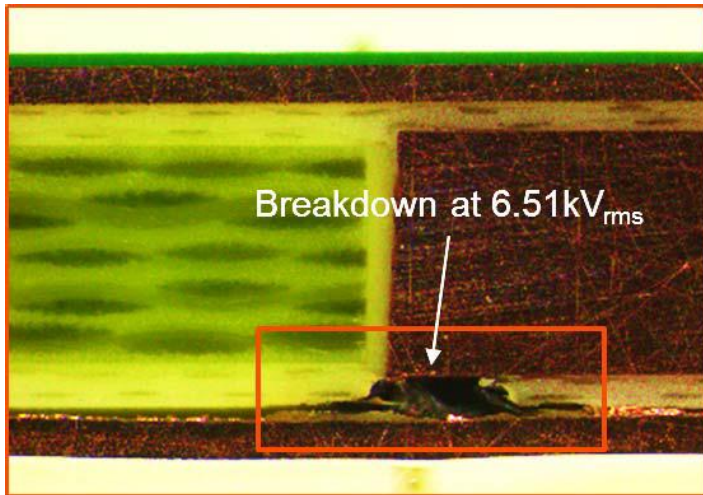
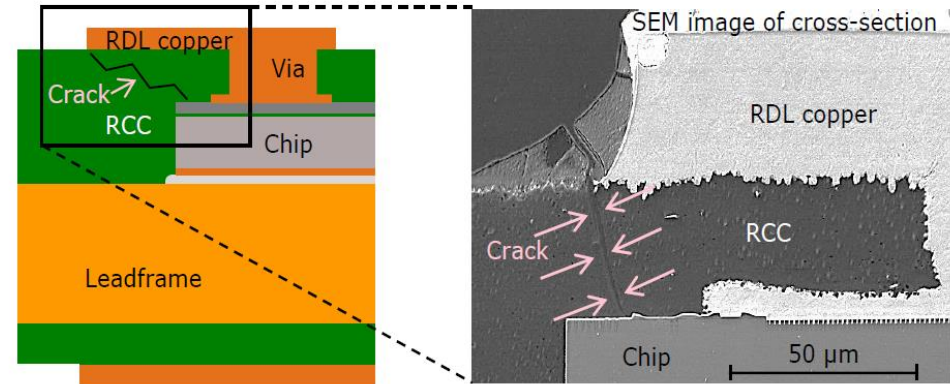
- 50% improvement in performance
- 4.5-9W ; 3-5 K rise in temperature;
- 0.05 -0.1 milliohm resistance



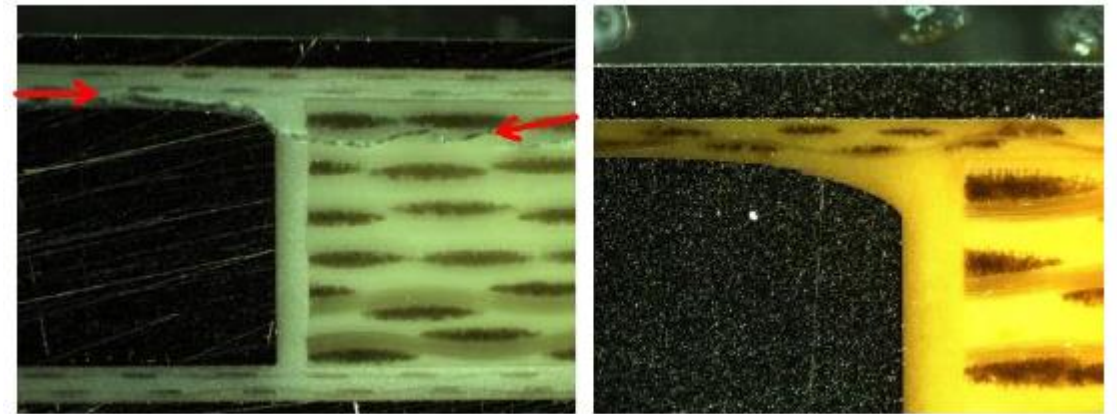
Reliability Challenges

- Cracking of thick vias
 - Dielectric cracking at stress-intensive points
 - Partial discharge:
 - 41-50 kVrms/mm before aging
 - 32-36 kVrms/mm after aging
- Lifetime = C/E^n
- n = 10-11
- n = 14-16

Infineon power module (low CTE, high Tg, high fillers or fibers)



ABB/Schweizer
Example of electrical breakdown at high fields



Bosch/Schweizer/Isola
Resin cracking in standard resins (left), no cracking with advanced epoxies

Low-Frequency - High-Power Magnetics

- Ferrite 3C90:
 - 500 kHz; 0.1 T peak; 700 mW/cc;
 - 1 MHz; 0.02 T; 70 mW/cc;
- Ferrite 3F5 MnZn:
 - 1 MHz; 0.02 T; 30 mW/cc
- Sumida's ferrite:
 - 1.5 MHz; 0.02 T; 37 mW/cc
 - 1 MHz; 0.02 T; 70 mW/cc;
 - 200 kHz; 0.1 T; 250 mW/cc

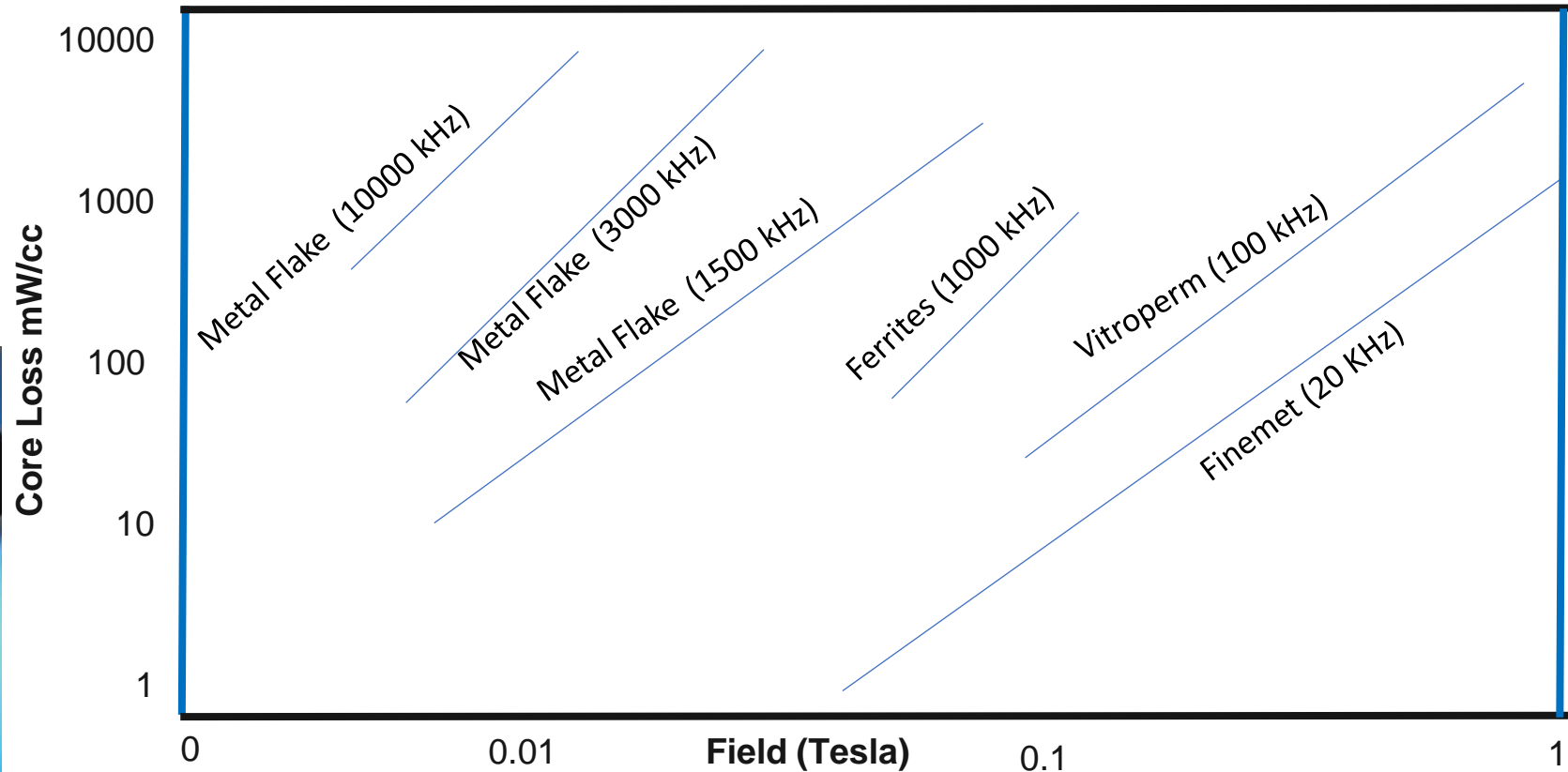
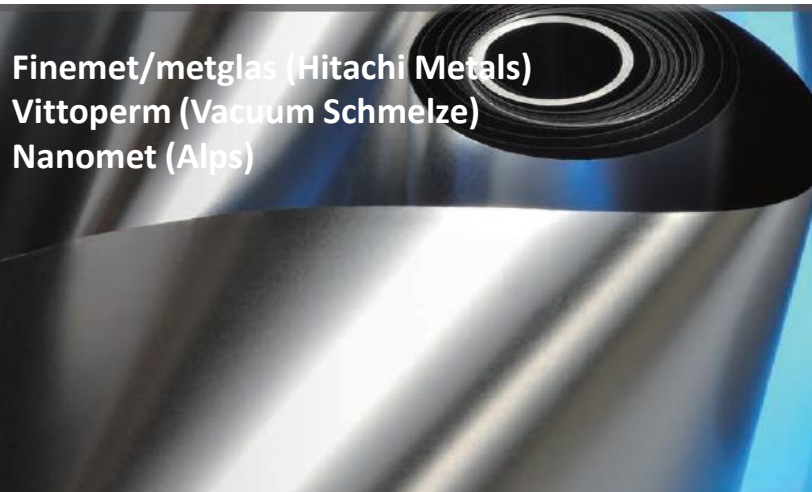
Vitrovac ($\text{Co}_{67} \text{Fe}_4 \text{B}_{11} \text{Si}_{16} \text{Mo}_2$) amorphous flakes:
 100 kHz; 0.1 Tesla, 30 mW/cc;
 100 kHz; 0.2 Tesla: 200 mW/cc;

Hitachi metals: Finemet - FT-3L and FT-3M:
 20 kHz; 0.1 Tesla; 2 mW/cc
 20 kHz; 0.2 Tesla; 15 mW/cc
 20 kHz; 1 Tesla; 300 mW/cc

Permeability of
 10,000 to 100,000
 20 kHz x 50 mT \ll 500 W/cc

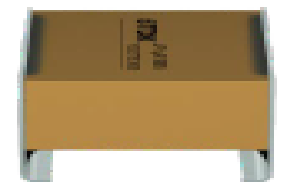
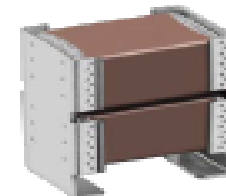
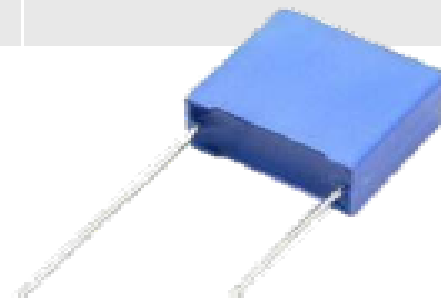
M_s : 1.5 – 2 Tesla;
 1-5 A/m of Coercivity
 < 100 kHz

Nanocrystalline films



Comparison of DC capacitors of nominal $1\mu\text{F}/400\text{V}_{\text{op}}$

	MKP film capacitor	BTO Class 2 MLCC (e.g. X7T)	CeraLink™
Nominal / rated capacitance	100 %	100 %	100 %
No bias voltage $0.5 V_{\text{RMS}}, 25^\circ\text{C}$	100%	100 %	35 %
DC link voltage $0.5 V_{\text{RMS}}, 25^\circ\text{C}$	100 %	35 %	60 %
DC link voltage $20 V_{\text{RMS}}, 25^\circ\text{C}$	100 %	35 %	100 %
Typical capacitance density @ DC link voltage $20 V_{\text{RMS}}, 25^\circ\text{C}$	$0.7 \mu\text{F}/\text{cm}^3$	$2.5 \mu\text{F}/\text{cm}^3$	★ $4.9 \mu\text{F}/\text{cm}^3$
Typical current rating per capacitance @ 100 kHz, 105°C	$<1 \text{ A}/\mu\text{F}$	$<4.5 \text{ A}/\mu\text{F}$	★ $12 \text{ A}/\mu\text{F}$



Heterogeneous Integration with Nanopackaging

- Power delivery in computing systems
 - Integrated voltage regulator: power conversion closer to the load
 - Capacitors and Inductors: >10 MHz; Impedance < 1 milliohms
- Medium-power packaging
 - Integrated copper carriers
 - Embedded-die packaging with die-attach materials: Silver to nanocopper
 - High-temperature organic packaging
- High-Power packaging:
 - Doubleside cooling, lower parasitics
 - High-voltage passives: 1000 V, planar and higher power densities